



# ***HAIR Based Sensing and Actuation***

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# Biomimetic HAIR-Based Sensing and Actuation

- Our focus: new sensor/actuators to meet constraints (SWaP + cost + performance) for micro air vehicles for ARL's MAST program, where COTS are unsuitable
- **Example:** *Air flow sensor for wind gust state estimation for stable MAV control*
- MAST air flow sensor requirements
  - Low power, stand-alone, robust
  - Measure gusting air flow in range of 0.1 to 10+ meters/sec
  - Fast sensor response for dynamic flight control: > 30 Hz, ideally 100 Hz
  - Determine gust direction: minimum resolution is four in-plane quadrant directions

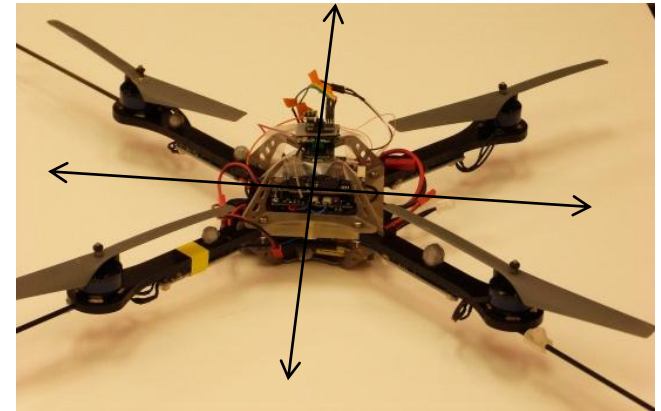
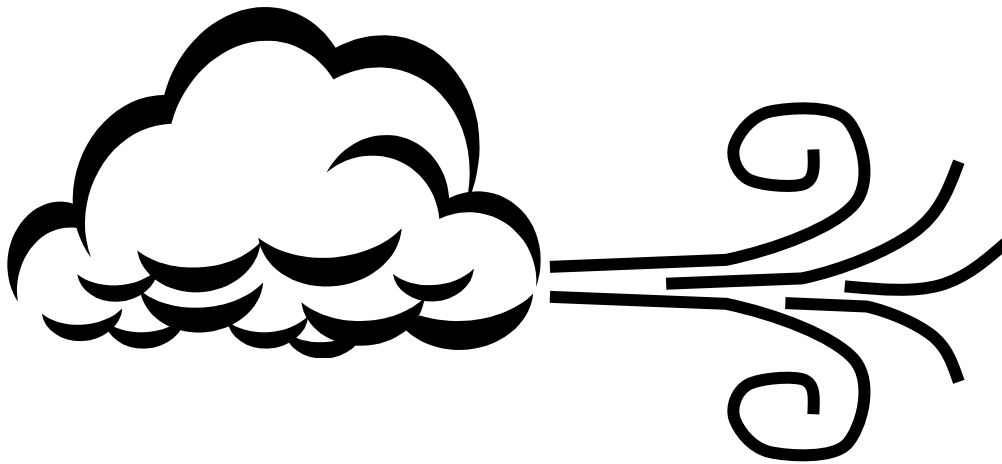
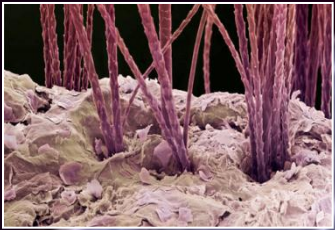


Image of U Maryland (J. Sean Humbert) macro-quadrotor

# Biomimetic Sensing

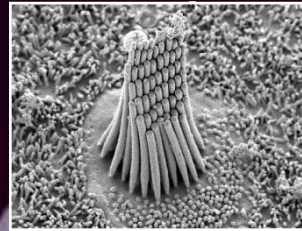
**Many different types of sensors are used in biological systems. The one structure that is used most abundantly is the HAIR.**

Gas/Chemical Sensing

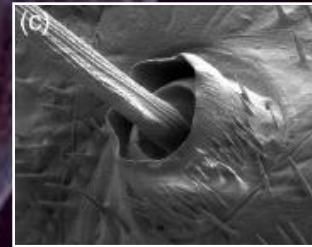


Filtering Particle Capture

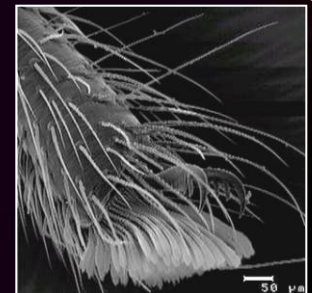
Cilia for Balance & Inertial



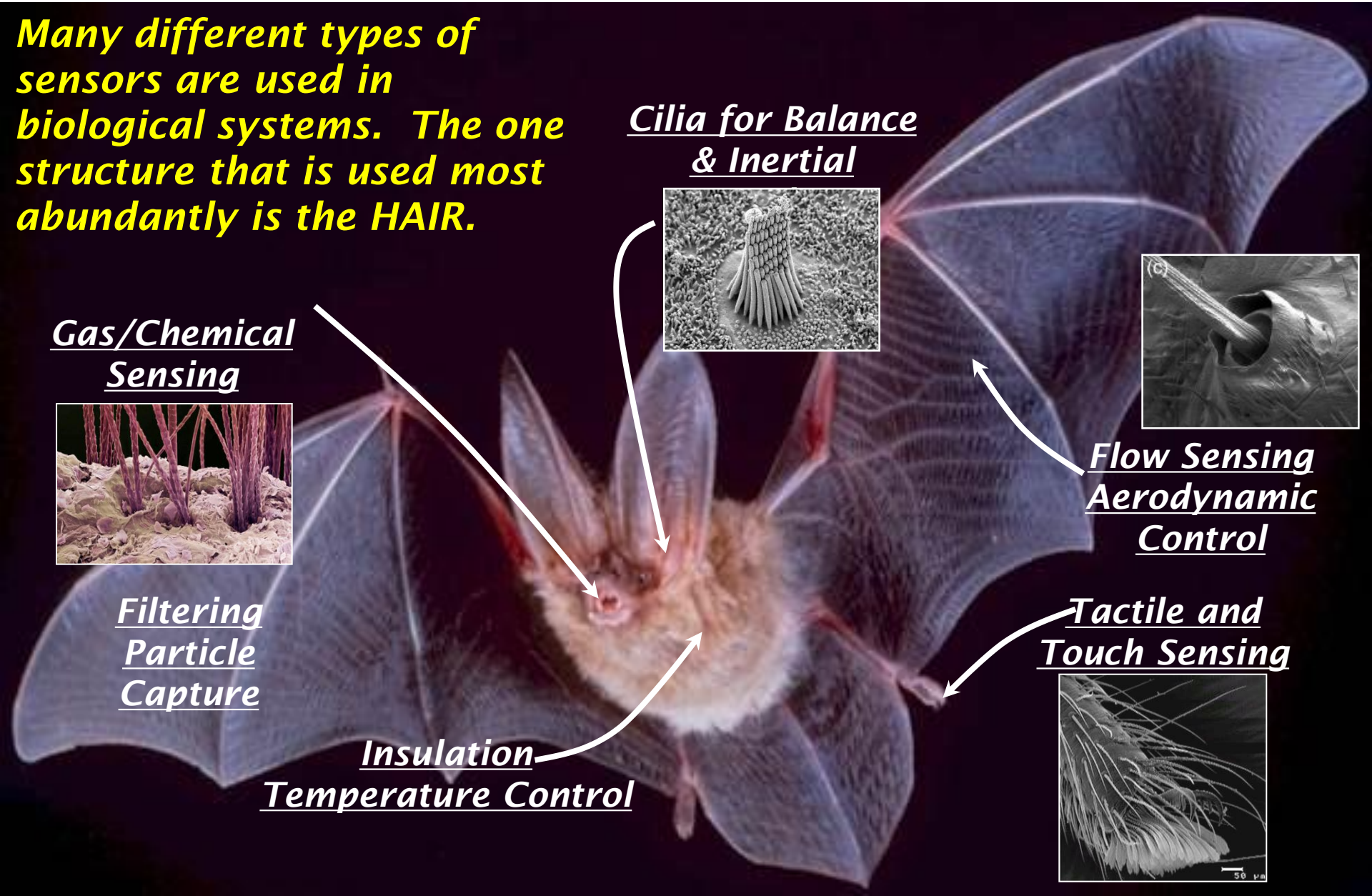
Flow Sensing Aerodynamic Control



Tactile and Touch Sensing



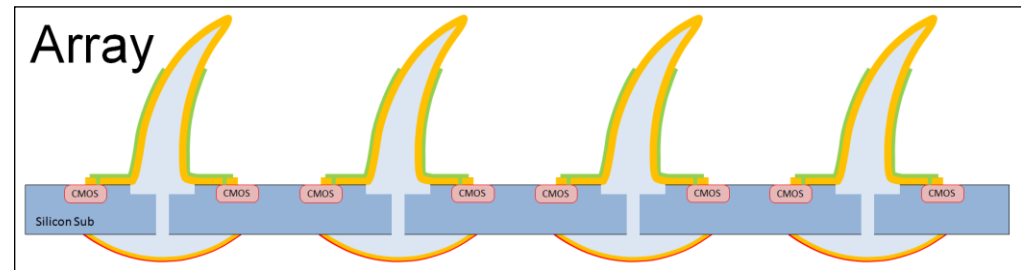
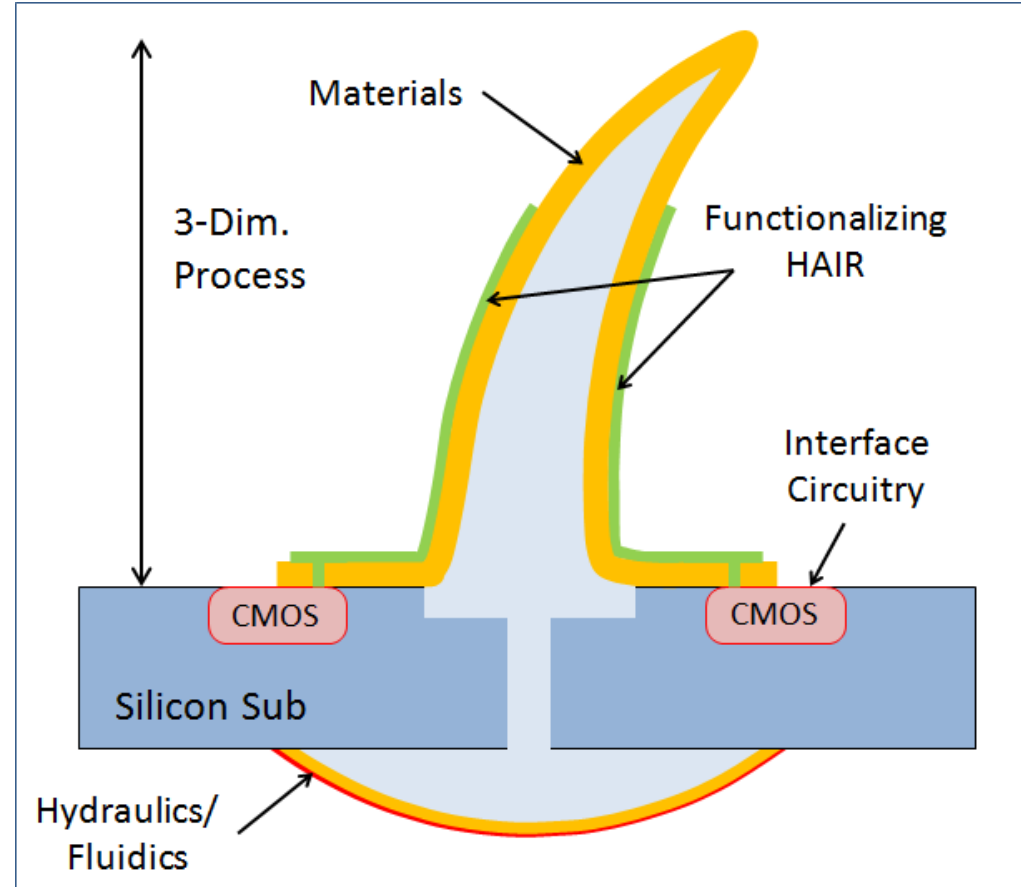
Insulation Temperature Control



# High-performance, Actuation and Integrated sensing Research (HAIR)

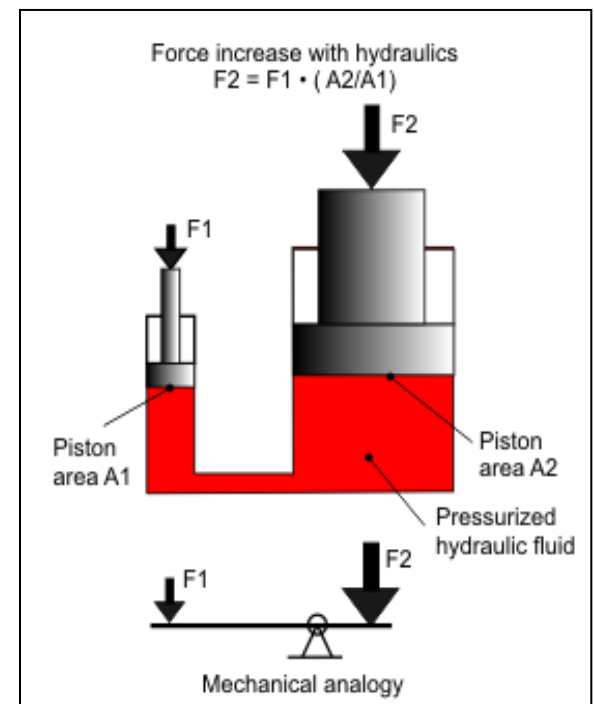
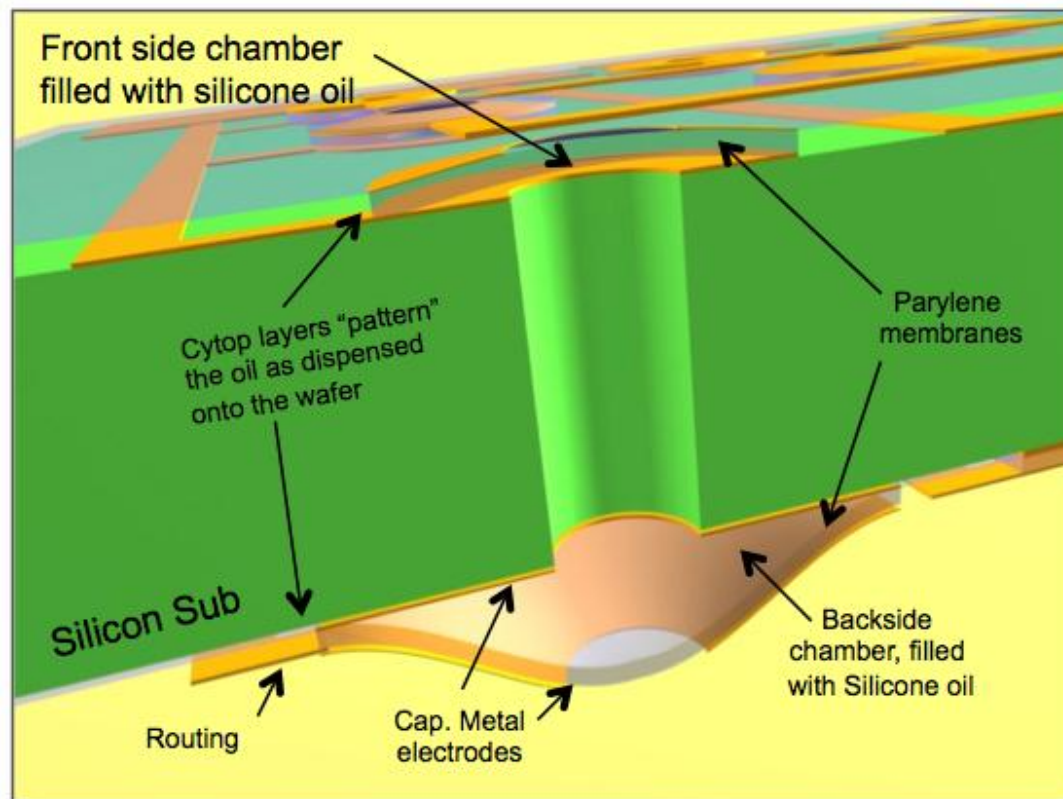
## Key biomimetic components

1. Material
2. 3-D Process
3. Hydraulics / fluidics
4. Functionalization
5. Circuit Integration
6. Array



# Electrostatic Micro-hydraulics

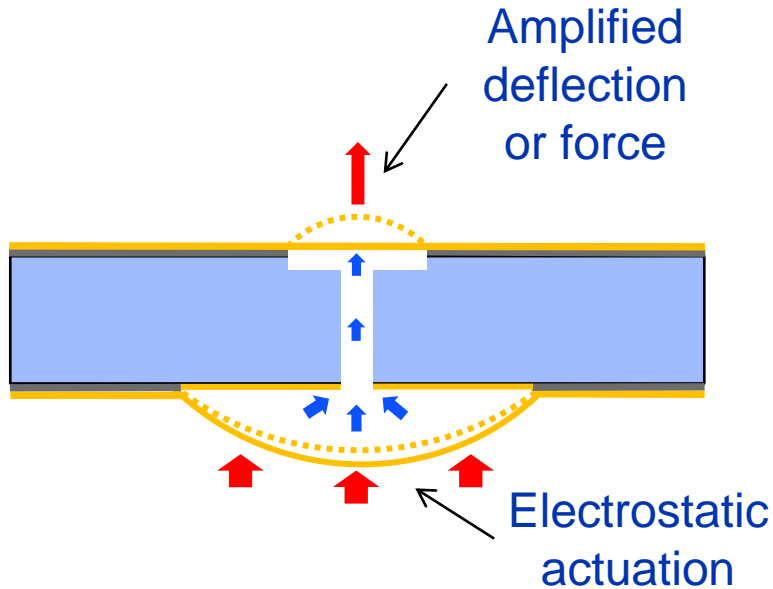
- Key concept: combine electrostatics & micro-hydraulics for large-force, large-deflection, low-power actuation and low-power, high-dynamic range sensing
- Structural features
  1. Two connected chambers on opposite sides of a wafer, capped with membranes
  2. Capacitive metal electrodes allow electrostatic actuation or sensing
  3. Encapsulated incompressible liquid dielectric constant  $> 1$  (i.e., air) increases capacitance thus improving electrostatic coupling





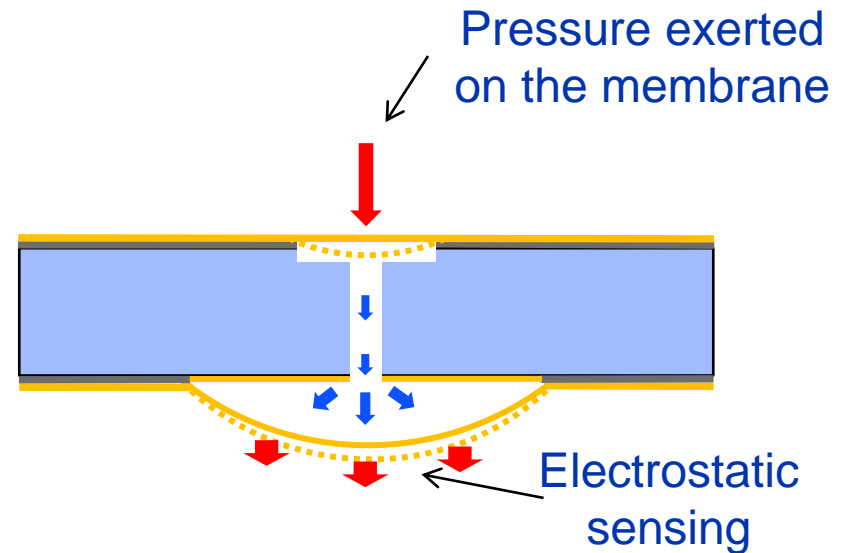
# Sensing & Actuation through Micro-Hydraulics

## Actuation Mode



- **Electrostatic actuation**
- Hydraulic amplification of force or deflection

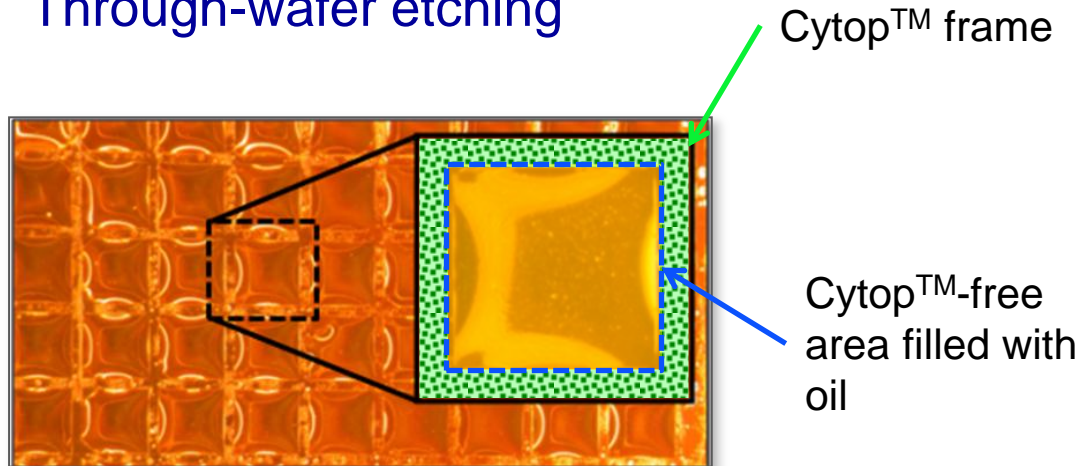
## Sense Mode



- External pressure applied (via touch, air flow, etc.)
- Hydraulic amplification of force or deflection
- **Electrostatic Sensing**

# Micro-Hydraulic Fabrication Process

1. Recess on both sides
  - Definition of capacitance gap
  - **Shape formation** of the liquid
2. Electrode on one/both side(s)
  - Actuation and/or sensing
3. Cytop™ layer and channel formation
  - Hydrophobic layer repels the silicone oil
  - Liquid will be contained in all the Cytop™-free areas
4. Through-wafer etching



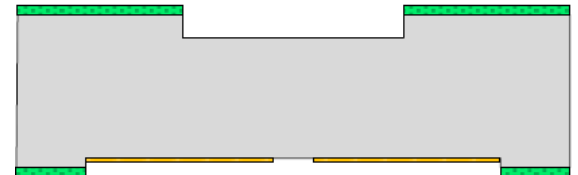
1) Trench etching



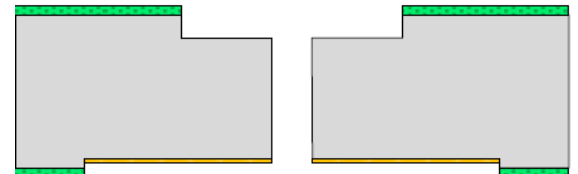
2) Cr/Au electrode



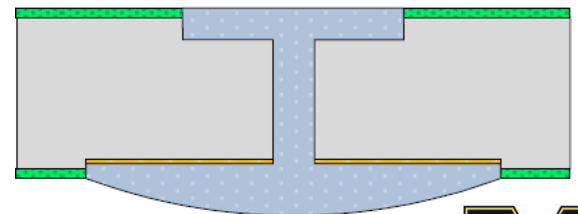
3) Cytop™ layer



4) Thru-wafer etching



5) liquid dispensing



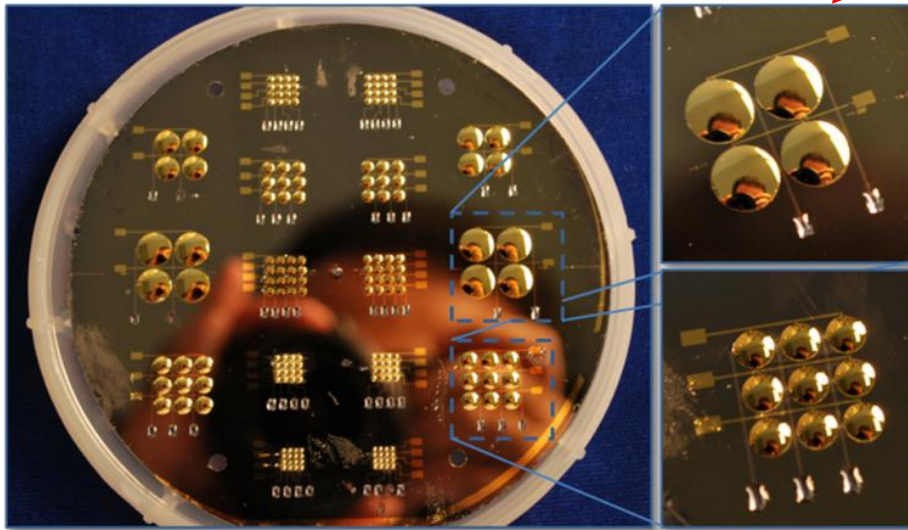
Sadeghi, Kim and Najafi, Digest MEMS 2010, pp. 15-18



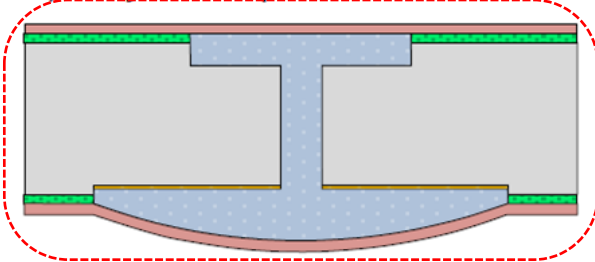
# Micro-Hydraulic Fabrication Process

5. Liquid dispensing
  - Liquid weight and surface tension on the back side are at equilibrium
  - → **double-sided process**
6. Parylene coating
7. Second electrode deposition

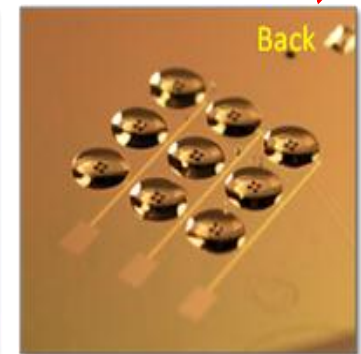
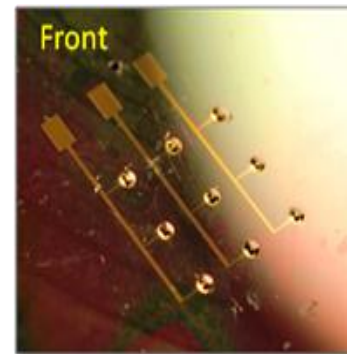
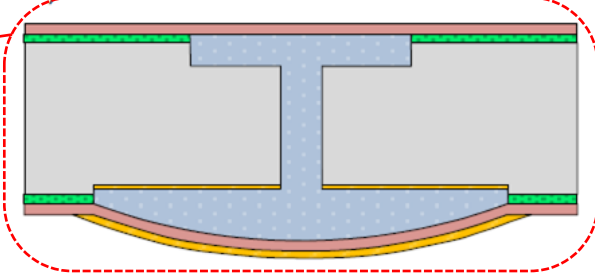
**Wafer level process for bubble-free liquid encapsulation**



6) Parylene deposition

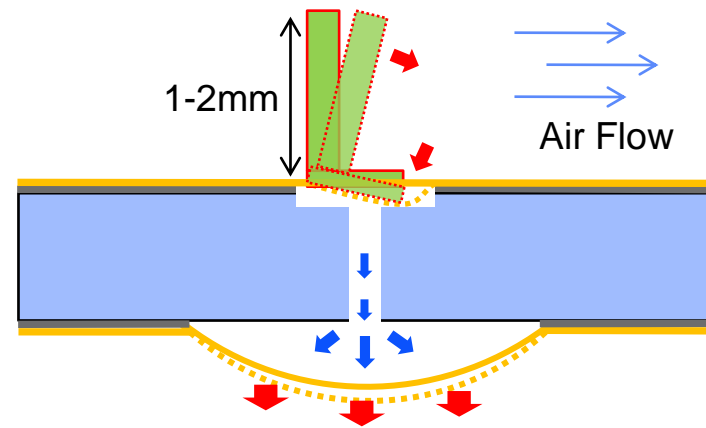
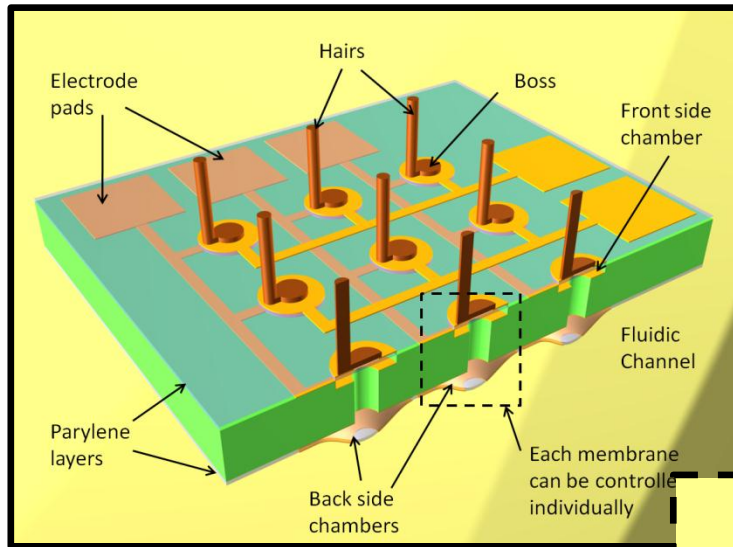


7) Cr/Au electrode

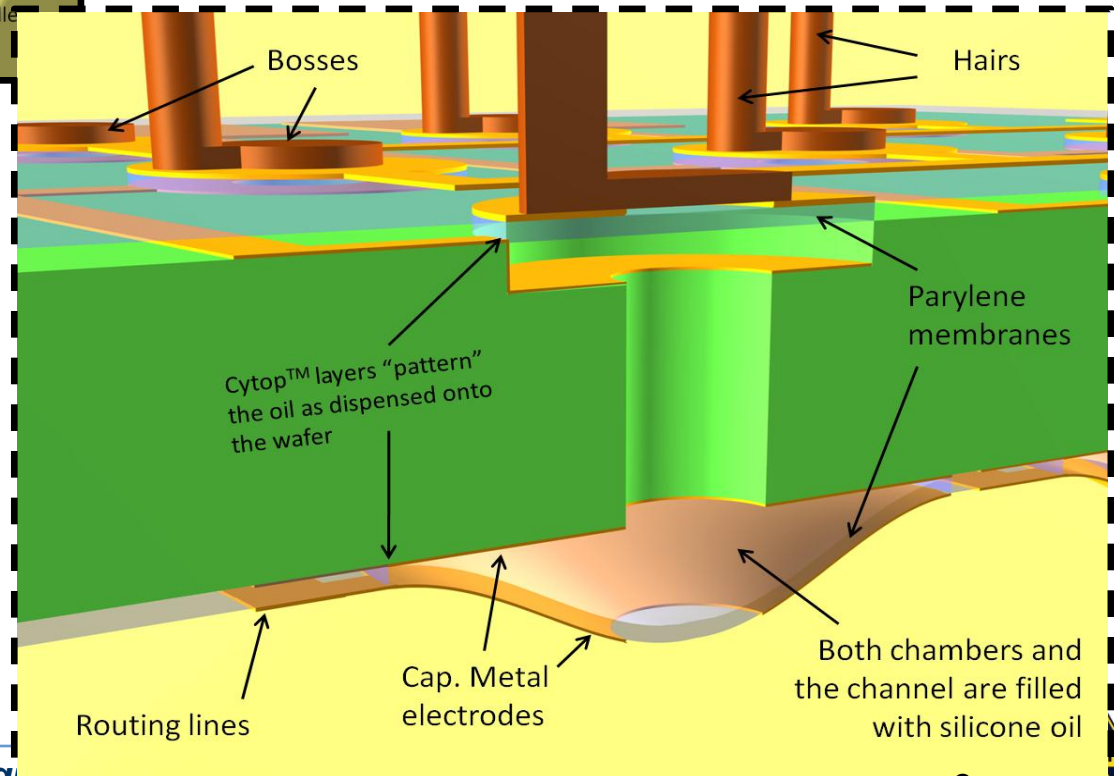


*Sadeghi, Kim and Najafi, Digest MEMS 2010, pp. 15-18*

# Airflow Sensor using Micro-Hydraulics

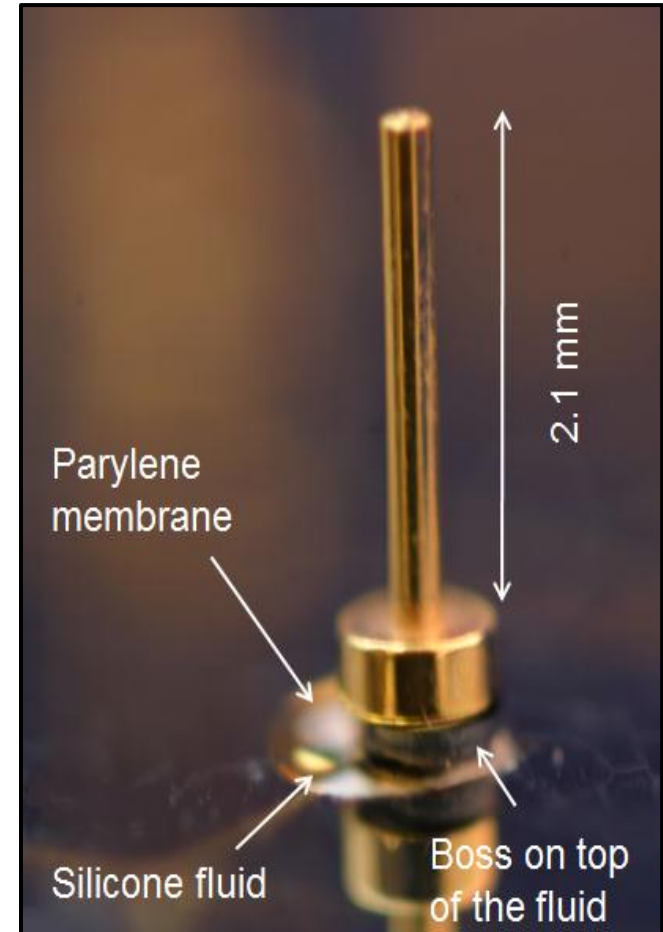
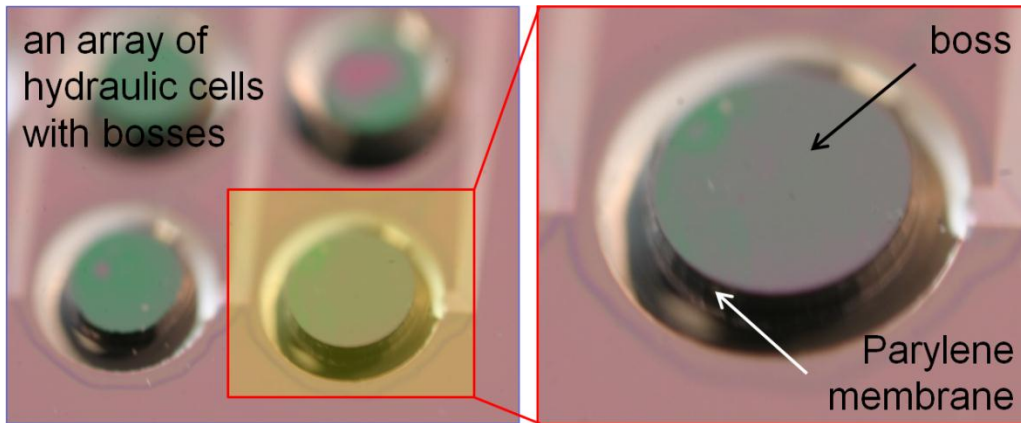
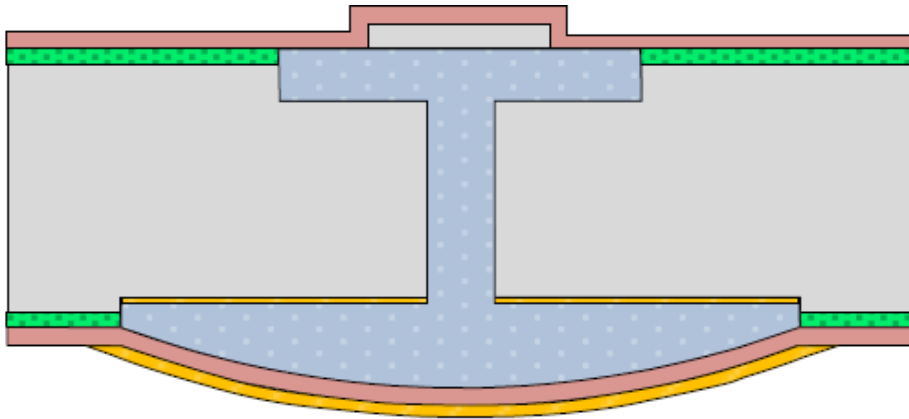


- **3-D boss + hair:**  
converts fluid drag force into pressure
- **Micro-hydraulics:**  
converts  $\Delta P$  into capacitance change
- **Arrays:**  
offer sensing of flow directionality



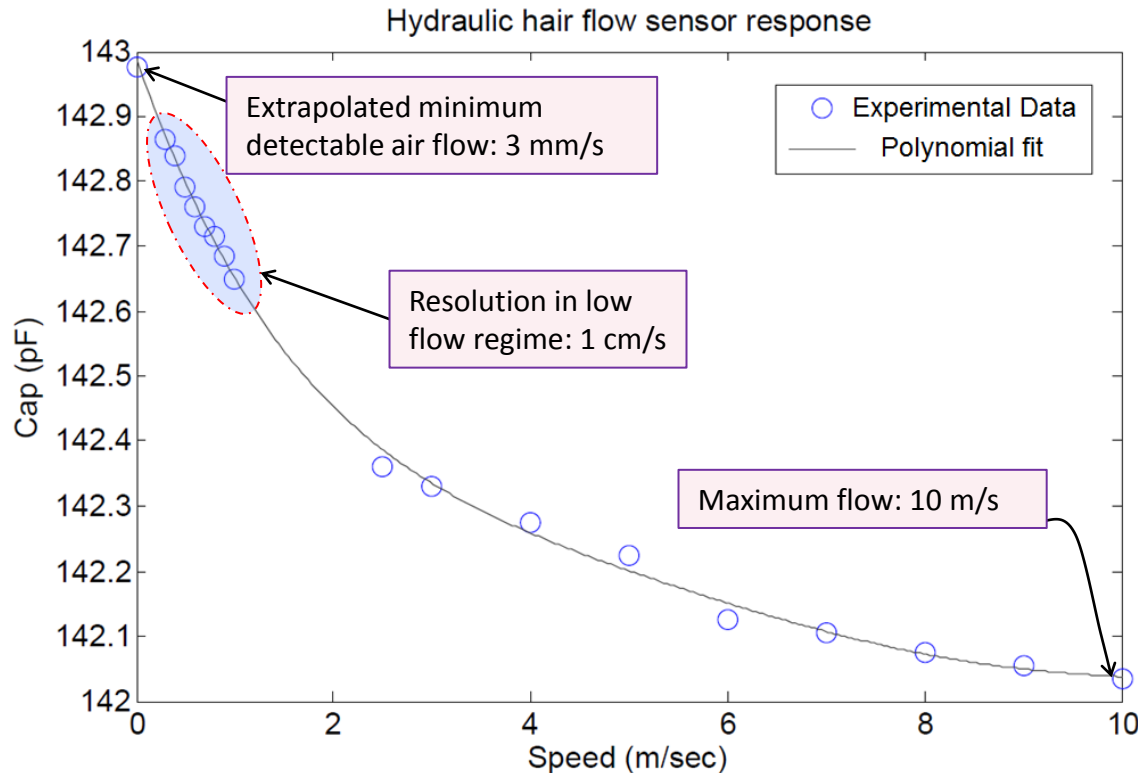
# Integration of Boss

- Self-aligned silicon boss acts as platform for attaching hairs
  - Boss is placed after liquid dispensing
  - After Parylene encapsulation, cilia is attached over boss



# 1<sup>st</sup> Generation Device, Experimental Results

- Average sensitivity\* = 333 fF/(m/s)
- Extrapolated minimum detectable air flow: **3 mm/s** assuming 1fF  $\Delta C$  detection
- Full scale range : **10 m/s**
- **But slow time response**

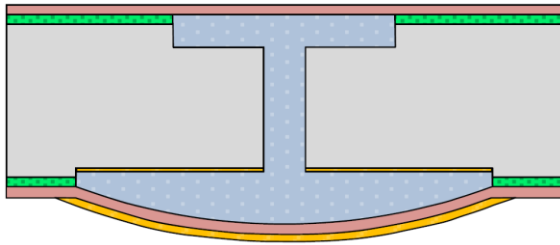


*Sadeghi,  
Peterson and  
Najafi, Digest  
IEDM 2011, pp.  
29.4.1-4*

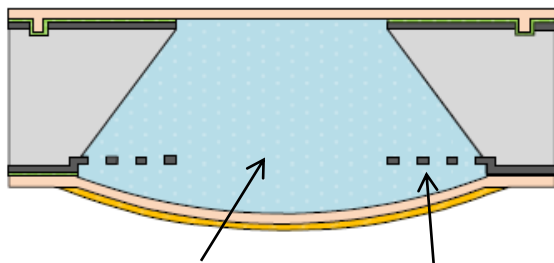
\* Tests on multiple samples of the same size yielded sensitivities of 230 to 440 fF/ms<sup>-1</sup>, with an average of 333 fF/ms<sup>-1</sup> over 10 m/s range (based on 5 samples)

# Reducing sensor response time

**Straight wall channel**



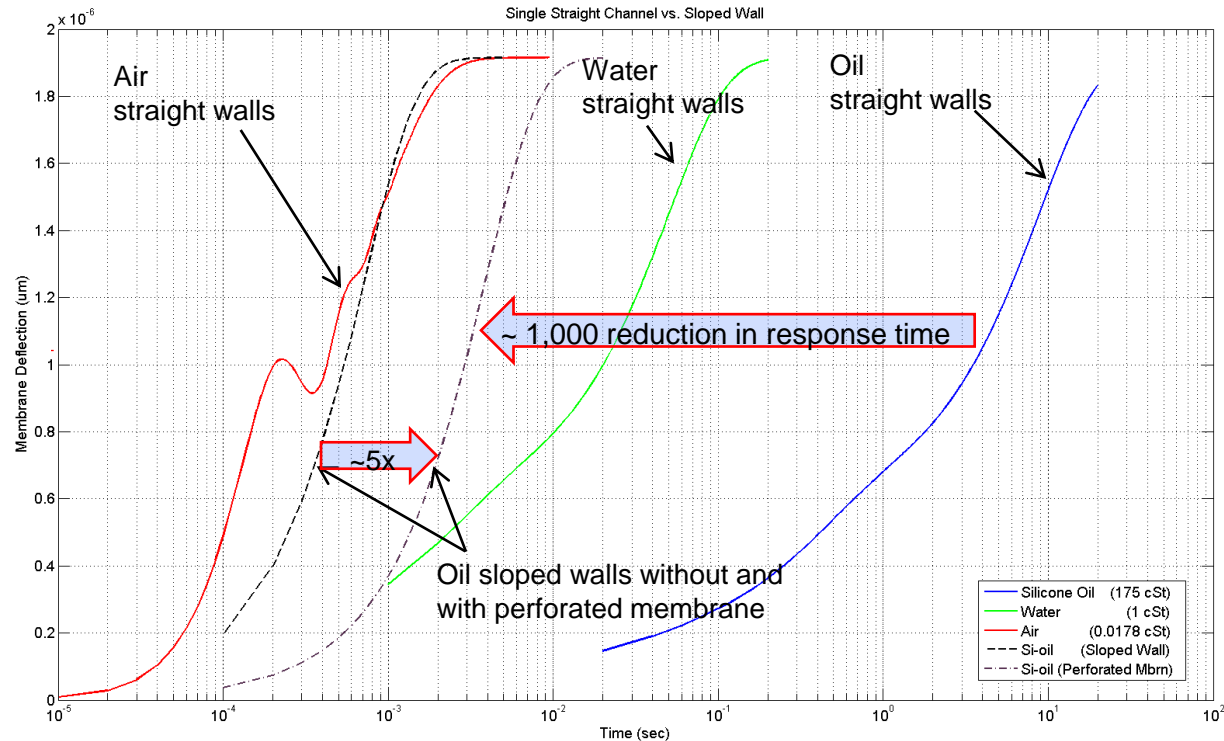
**Sloped wall channel**



Opening

Perforation structure

**Straight vs. Sloped Walls Response time**



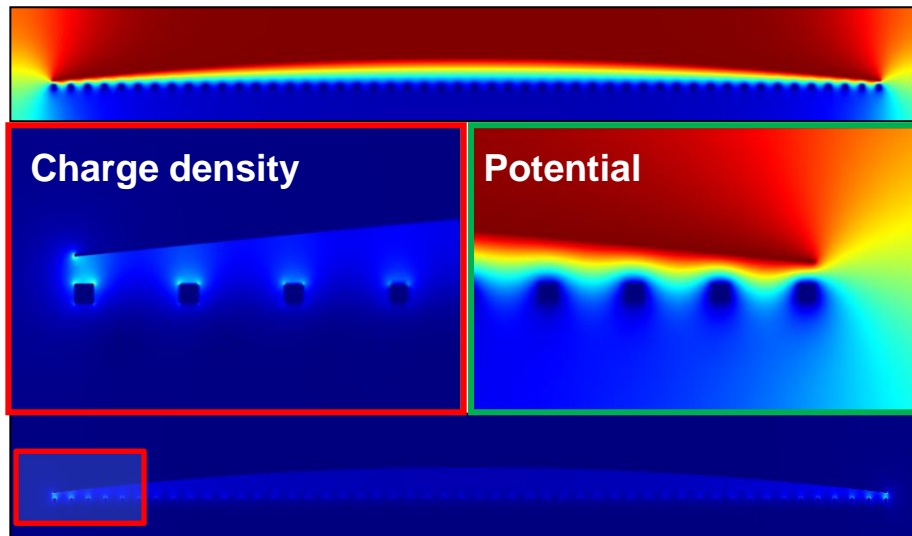
- Could reduce viscosity of fluid, but integration challenges
- Sloped wall design sufficiently reduces response time by  $\sim 1,000\times$



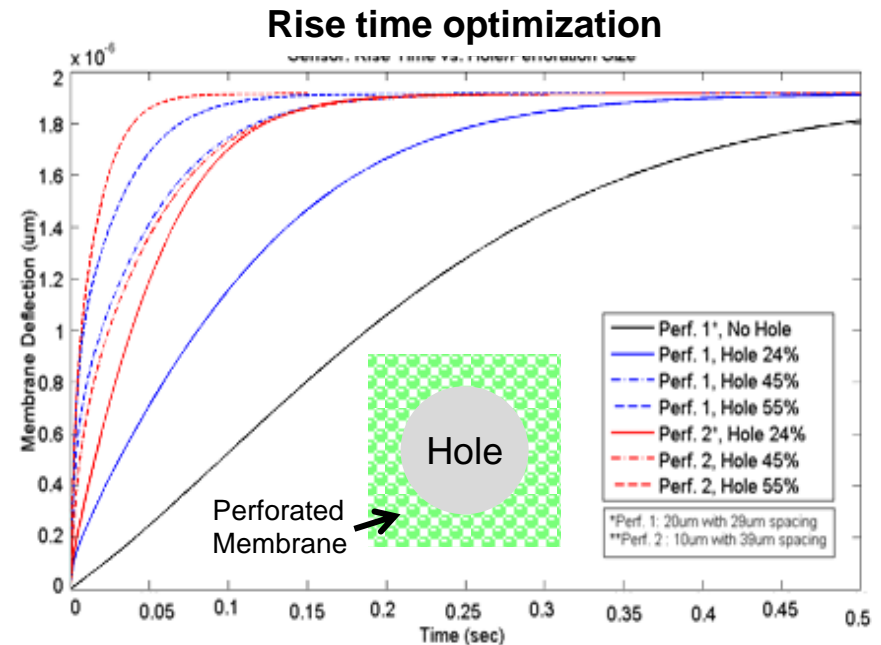
# FEM to optimize perforated membrane

- Trade off between area (i.e. capacitance and therefore sensitivity) and fluidic resistance (i.e. time response)
- Optimize Parylene thickness for symmetric rise/fall response  $\rightarrow 2\mu\text{m}$

**Greatest capacitance contribution comes from edge where gap is narrow  $\rightarrow$  put hole in membrane**



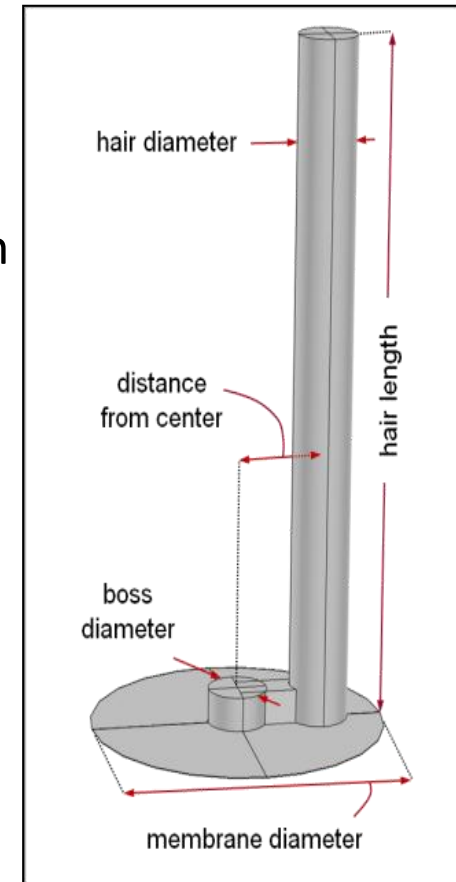
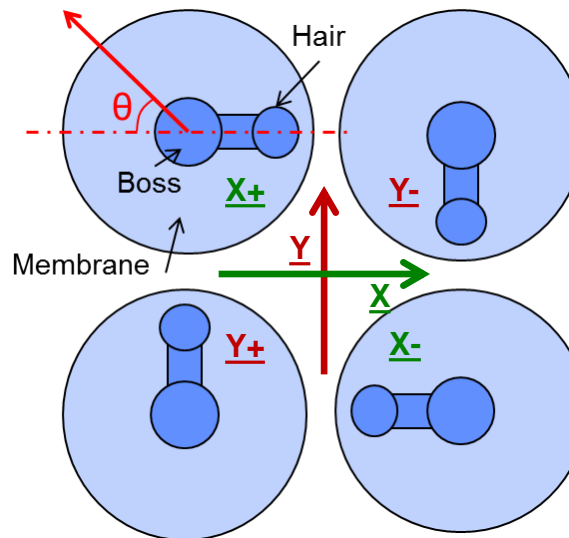
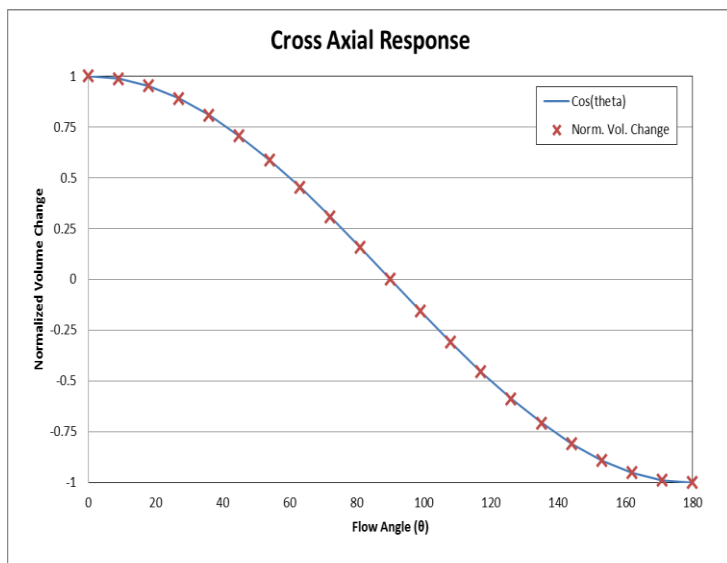
**Using perforations at periphery speeds up fluid flow but only slightly reduces capacitance**





# Hair placement and sensor array for directionality

- **Optimize hair/boss location**
  - Hair location to maximize membrane deflection → 56% of radius
  - Boss size to maximize deflection →  $50\mu\text{m}$
- **Directional Sensing**
  - Four cells / two pairs, each responsible for one direction



# 2<sup>nd</sup> Generation Hydraulic Fabrication

New process steps

1) Trench etching



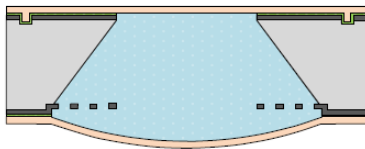
3) DRIE front and back



5) Cytop™ layer



7) Parylene deposition



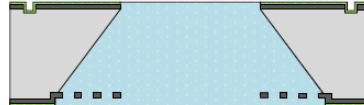
2) Deep boron doping



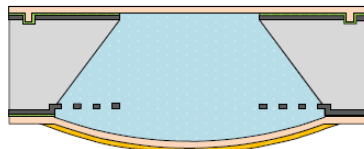
4) Anisotropic Si etching (EDP)



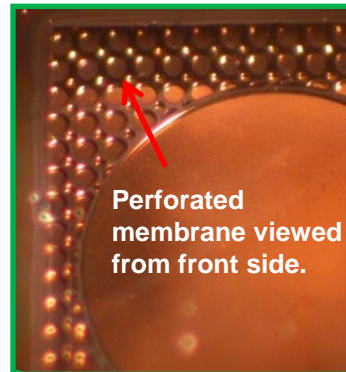
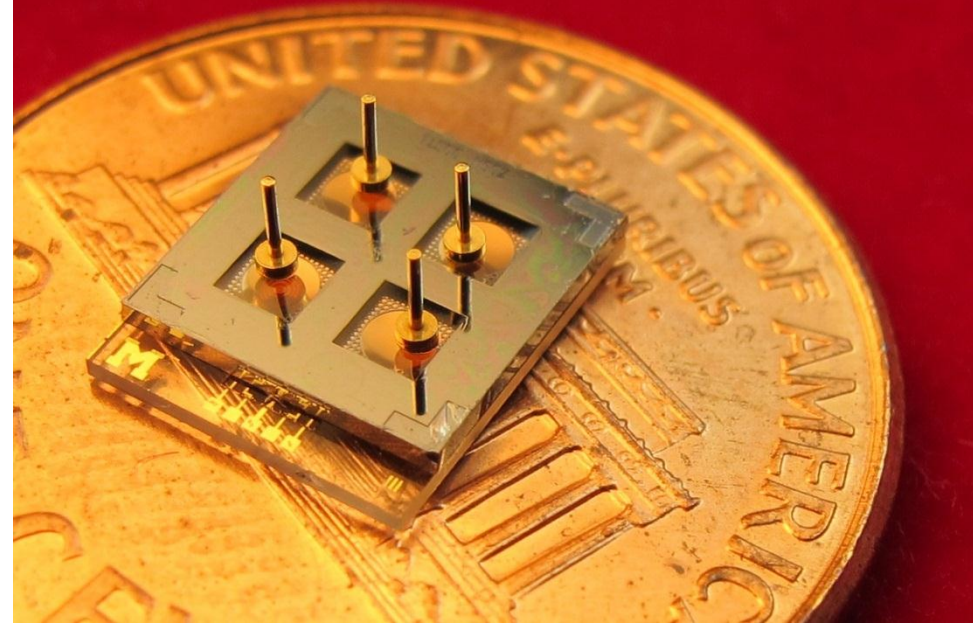
6) Liquid dispensing



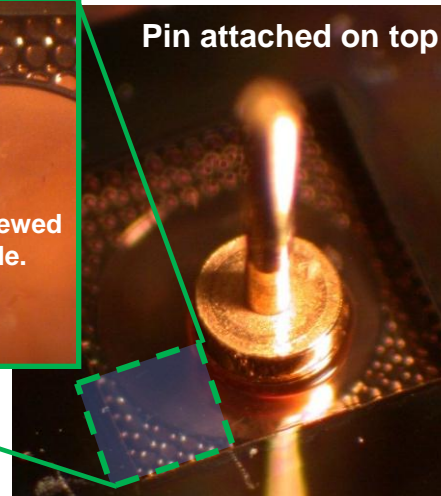
8) Metal deposition (Cr/Au)



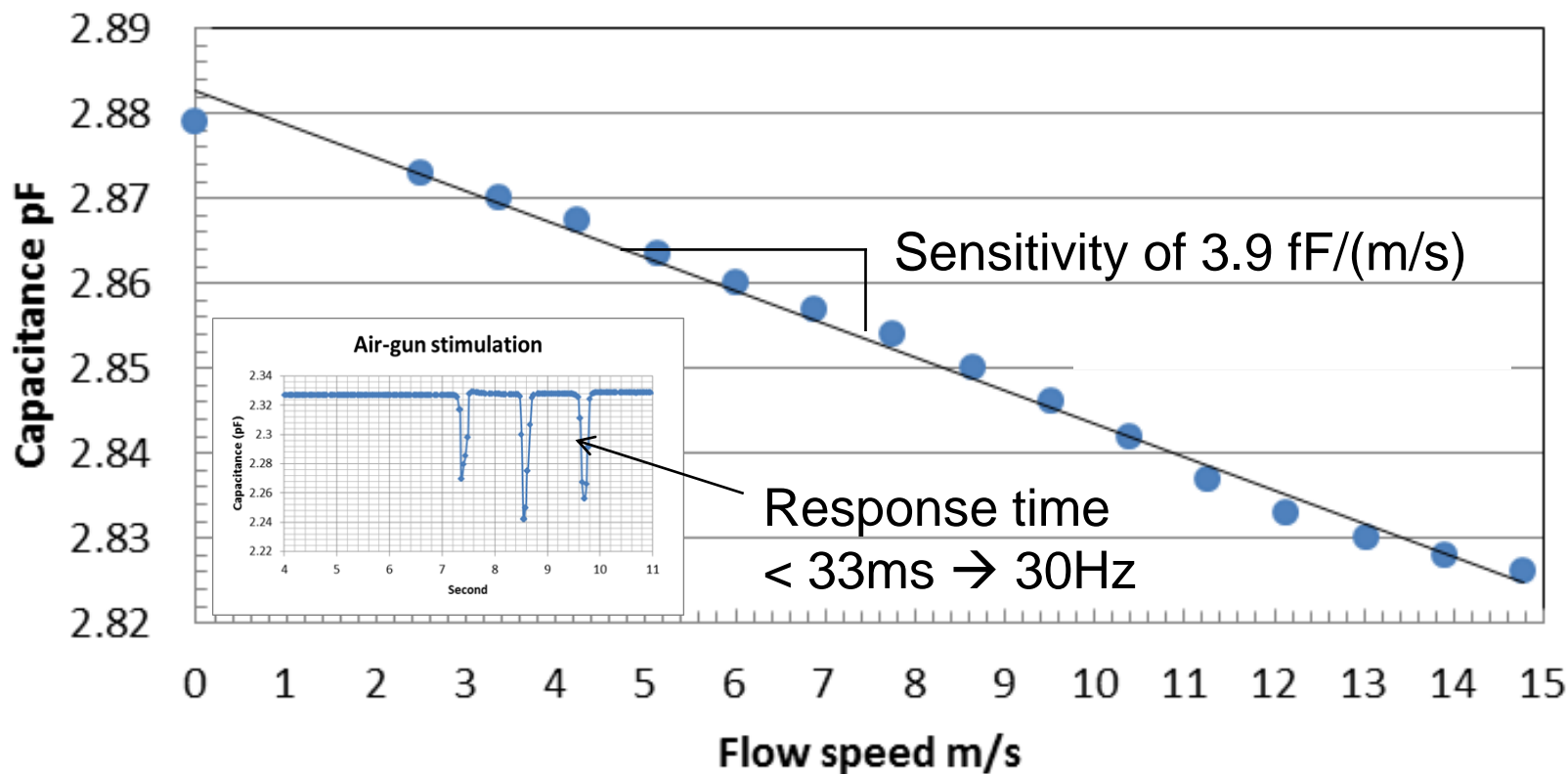
Fabricated and packaged hydraulic sensor



Pin attached on top

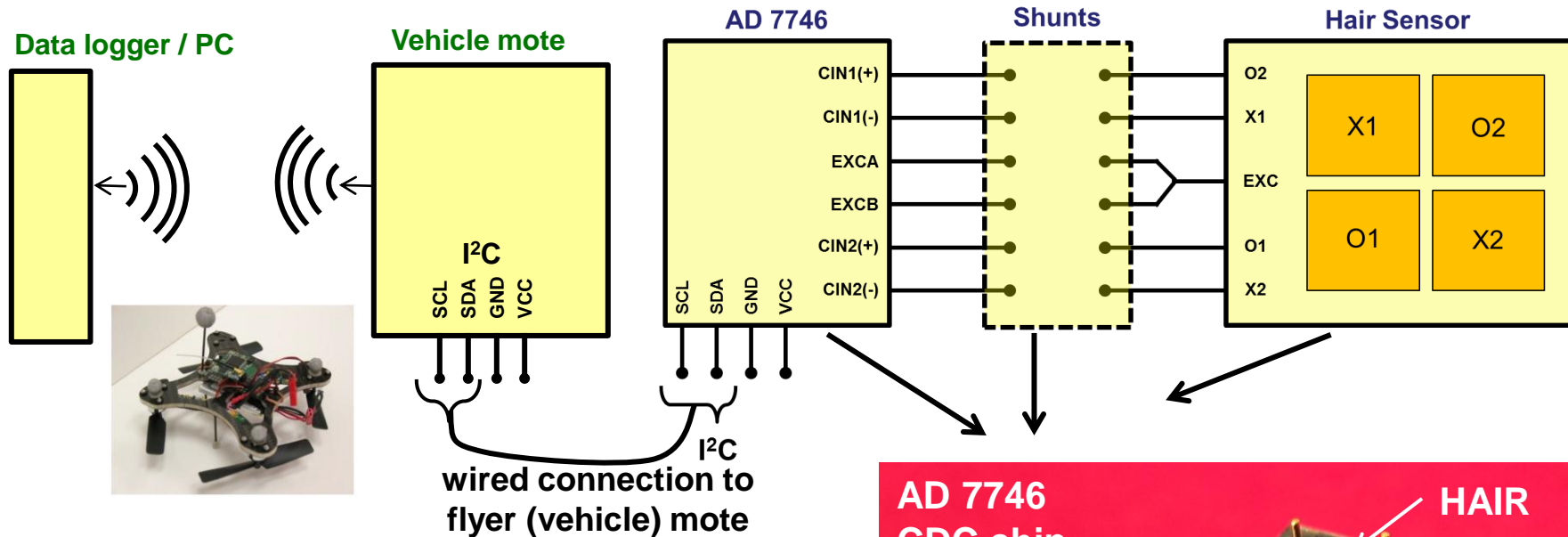


# Wind Tunnel and Air gun Tests



- Linear sensor output with sensitivity of 3.9 fF/(m/s) air flow
- **Full scale range: > 15 m/s**
- **Resolution: ~ 2 cm/s**, when in single-ended mode (noise = 80 aF)
- **Response bandwidth ~ 30 Hz**

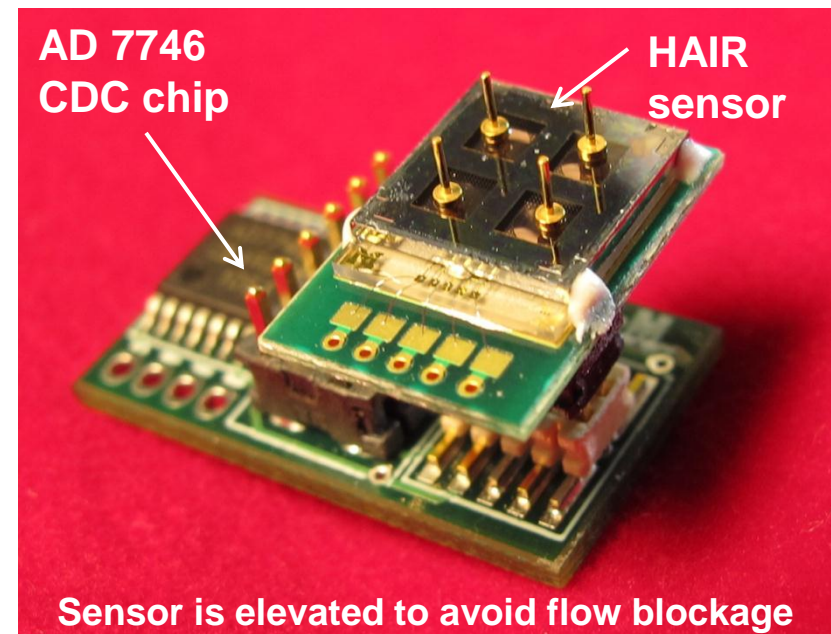
# Air Flow Sensor Integration & Performance Summary



Range*	0 – 15 m.s <sup>-1</sup>
Sensitivity	3.9 fF/(m/s)
Resolution*	~2.0 cm.s <sup>-1</sup>
Response time	~30 ms
Supply	3.3 -5 V
Power	3.5 mW
Weight**	1.2-1.5 g
Output	I <sup>2</sup> C

\* When read in single ended mode. Resolution in 2 channel mode is ~0.5 m/s, and the range decreases to approx. 2.5-15 m/s.

\*\* 1.2g without header, 1.5g with header



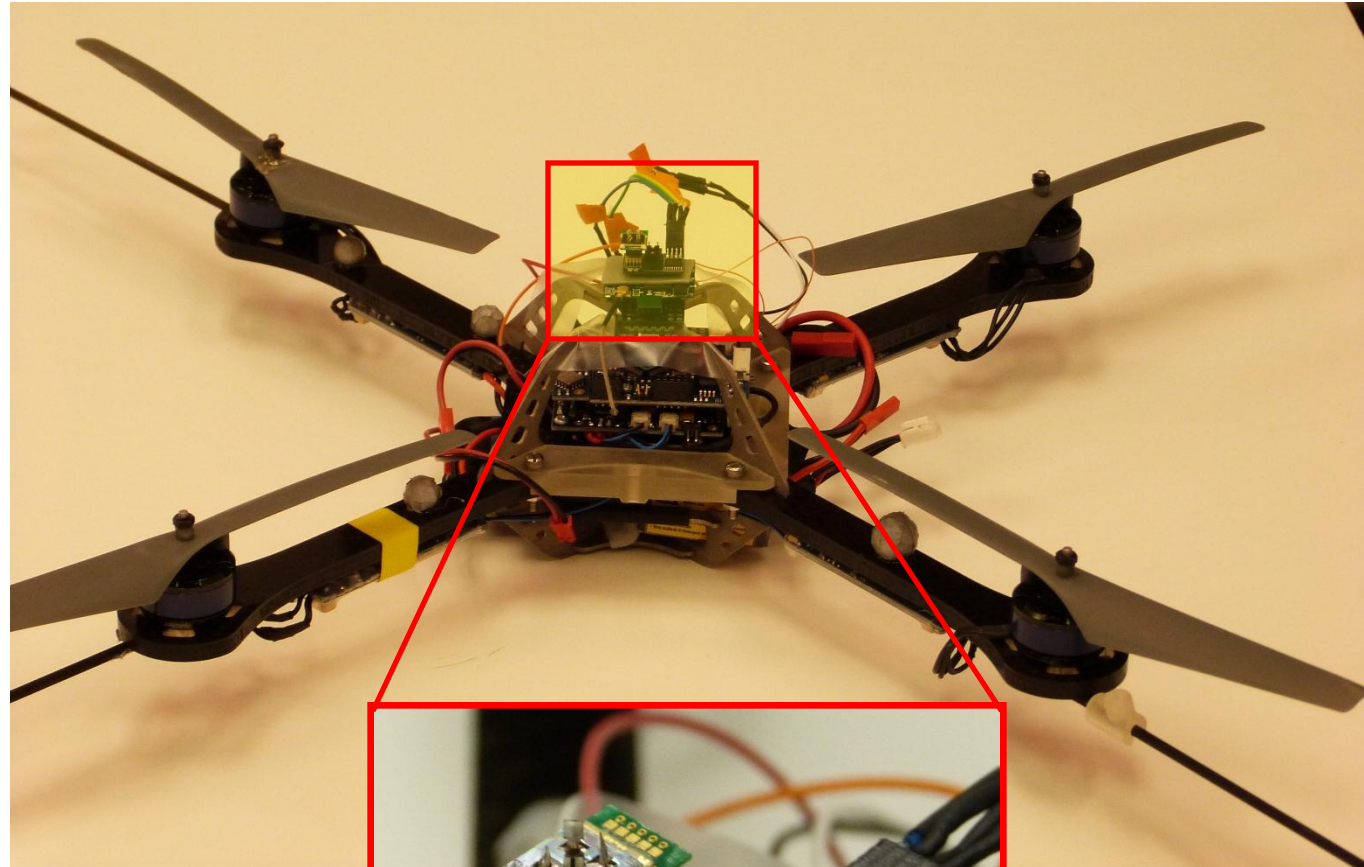


# Air Flow Sensor Integration on Flyers

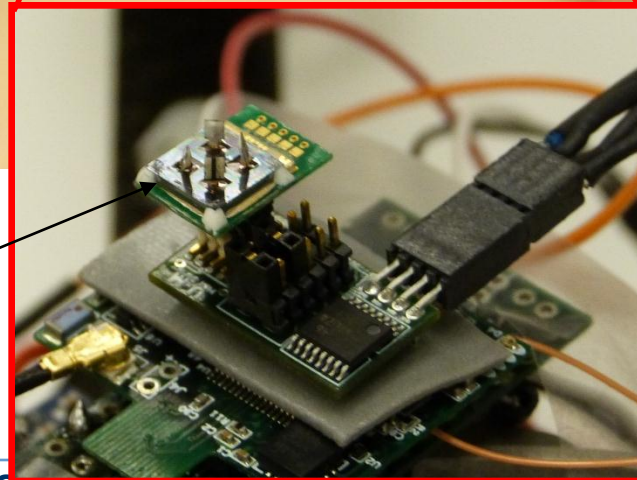
Collaboration with  
Prof. Sean Humbert,  
UMD

Wind gust detection  
with hydraulic HAIR  
directional air-flow  
sensors:

- ✓ Sensor is integrated with flyer mote
- ✓ Data transfer established
- ✓ Closed loop control of vehicle forthcoming

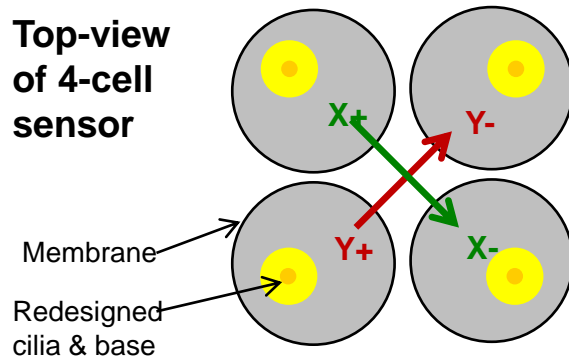


Air flow  
sensor  
and circuit

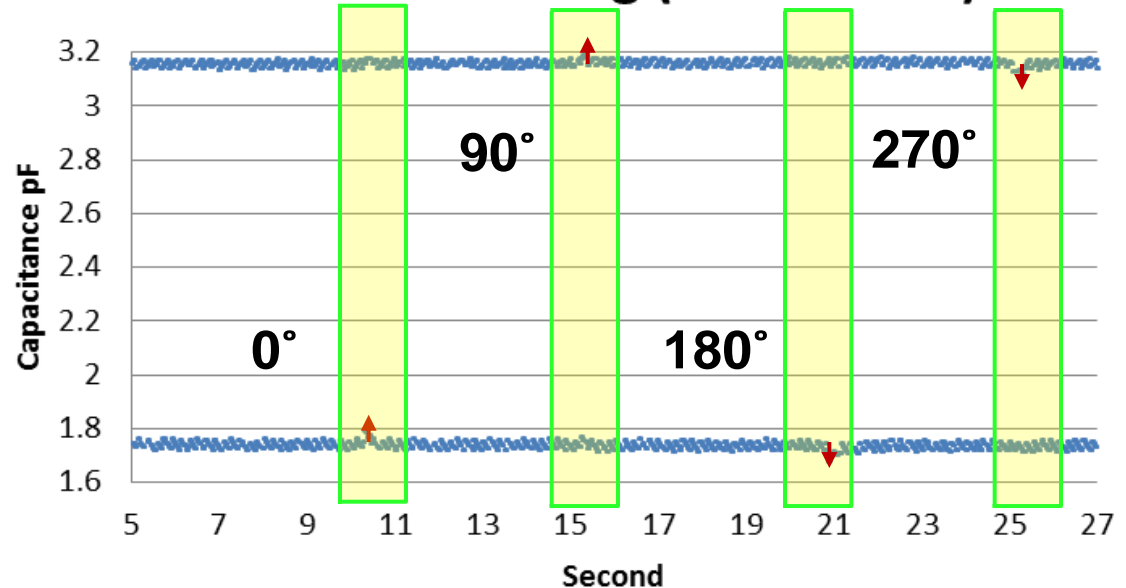


# Preliminary Results on Directional Sensing

Top-view  
of 4-cell  
sensor



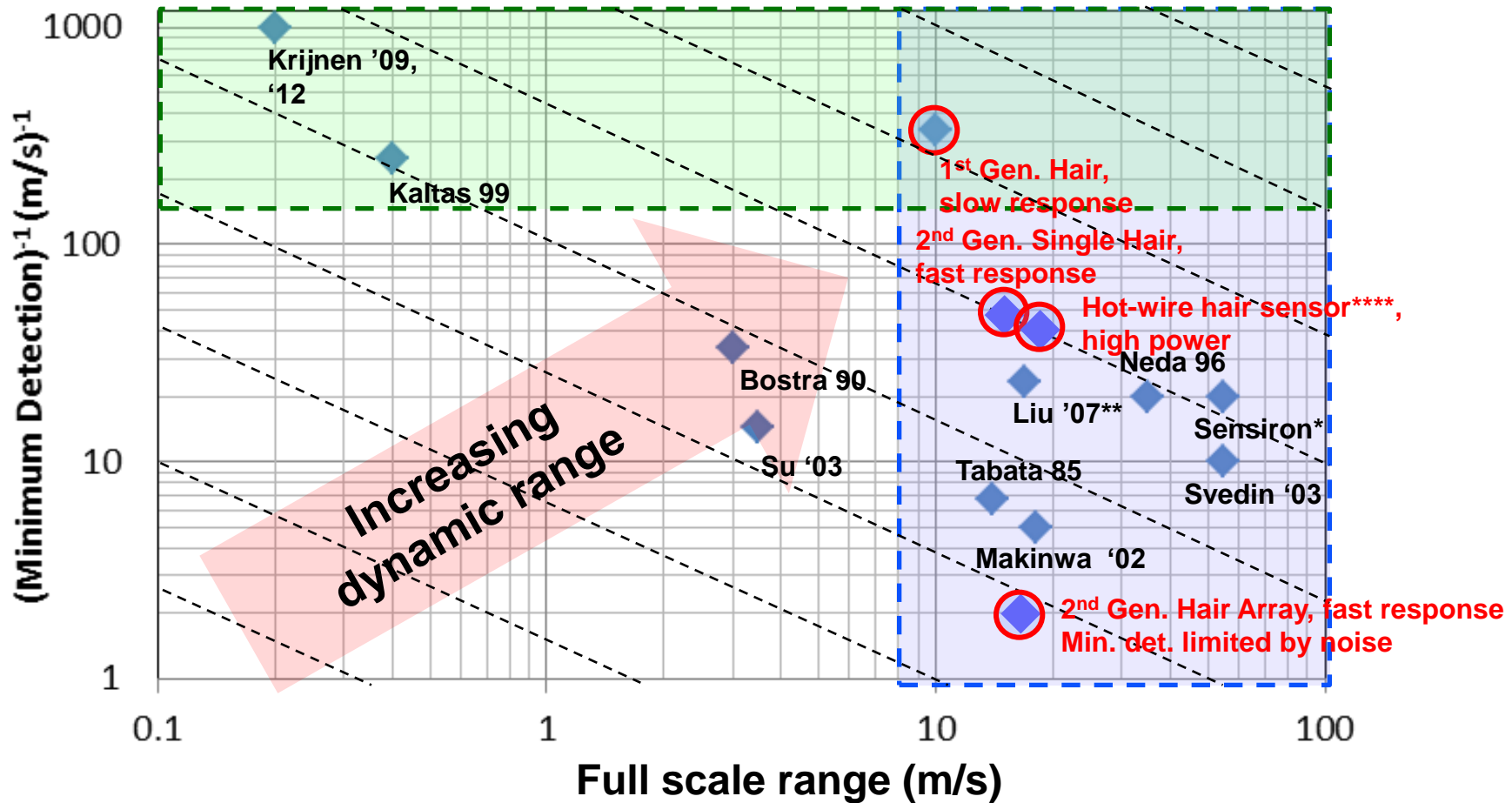
Directional Sensing (Differential)



- For dynamic flight control, need flow directionality
- Redesign cilia + two sensor pairs for in-plane flow vector determination
- Each pair is differentially measured by AD7746 CDC
- Resolution is reduced due to ~100x higher noise level: noise increases from 80aF (single-ended mode) to 10fF (dual channel mode)
- Circuit improvement are ongoing



# Trade off between full-scale range and min. detection



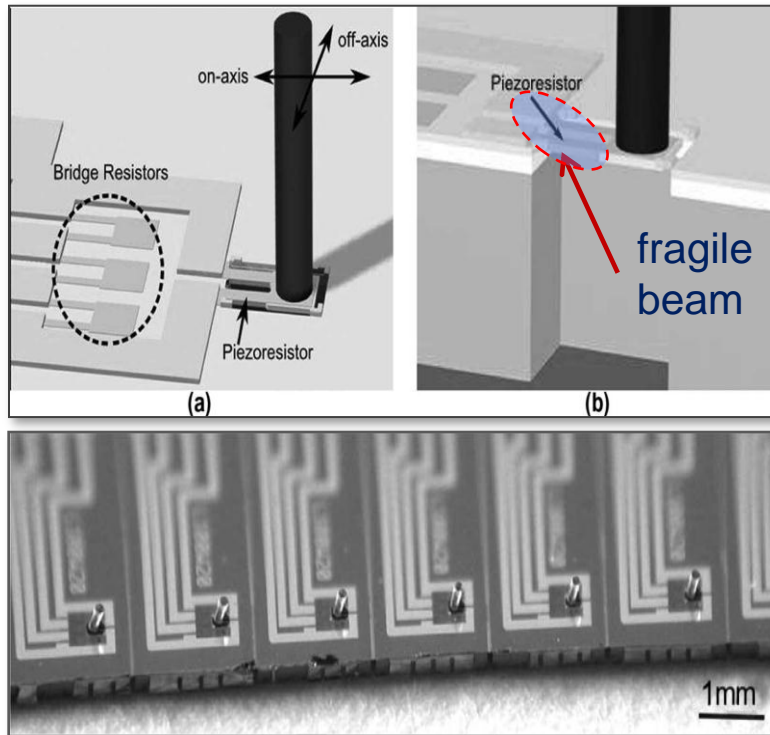
\* One of the finest commercially available MFS, Converted data from DS

\*\* The paper states min det. for water flow, not air. 5cm/s is based on our calculation

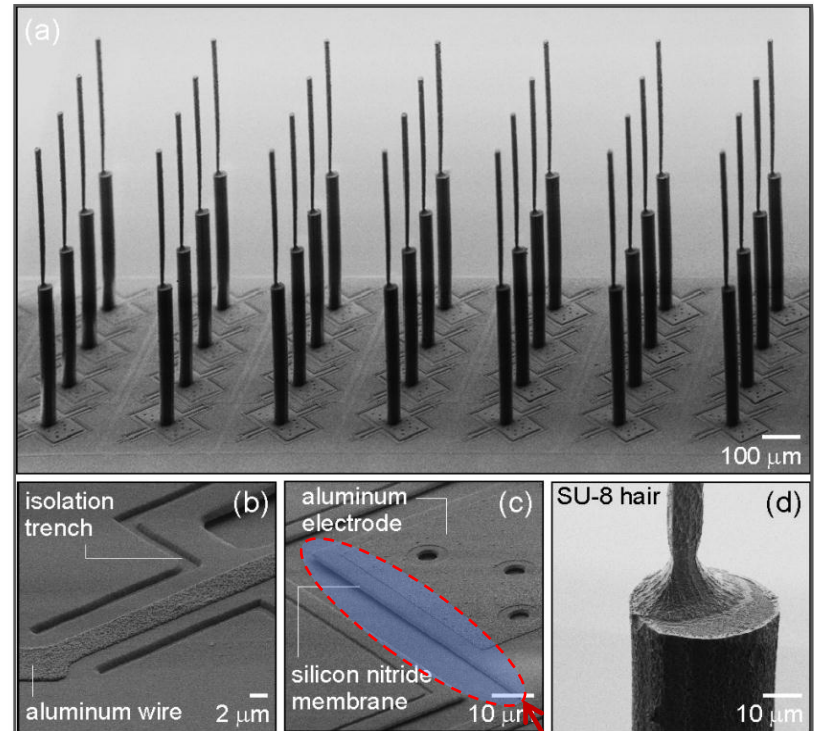
\*\*\* Minimum detection limits for data points that are not stated clearly are extracted from measurement graph data points, or assumed to be 0.01 of full-scale range.

\*\*\*\* Published at the Army Science Conference 2010 by Sadeghi, Peterson & Najafi

# Alternate Hair-Sensing Schemes



Chang Liu, et al. JMEMS 2007

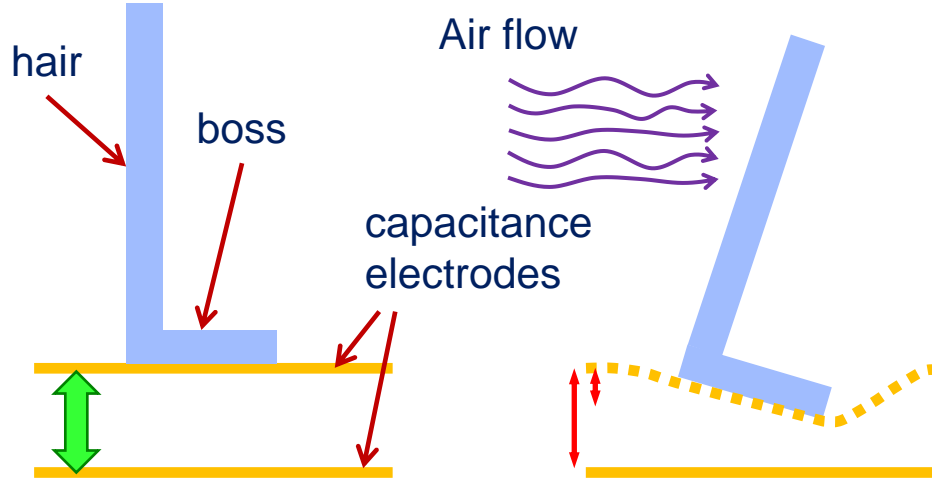


G.J.M. Krijnen, et al. MEMS '09

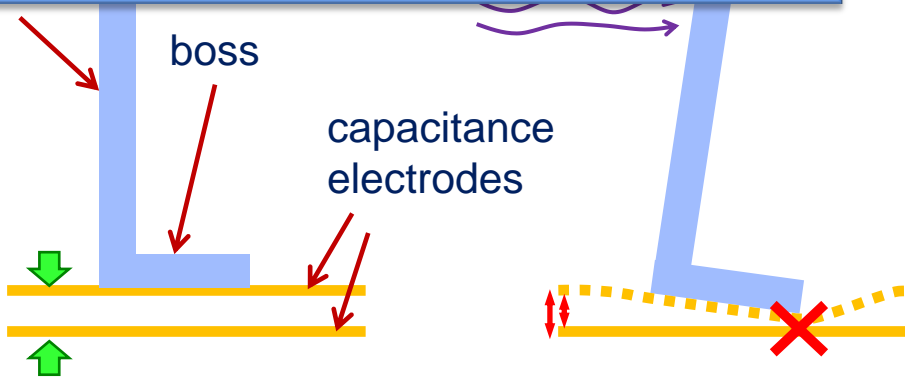
very narrow gap

- Existing approaches: Exposed piezoresistive beam or capacitive gap
- Liquid encapsulation encloses the capacitive gap, offering **robustness and improved dynamic range/resolution**, and **enables new applications** such as sensing in liquid or harsh ambient environments

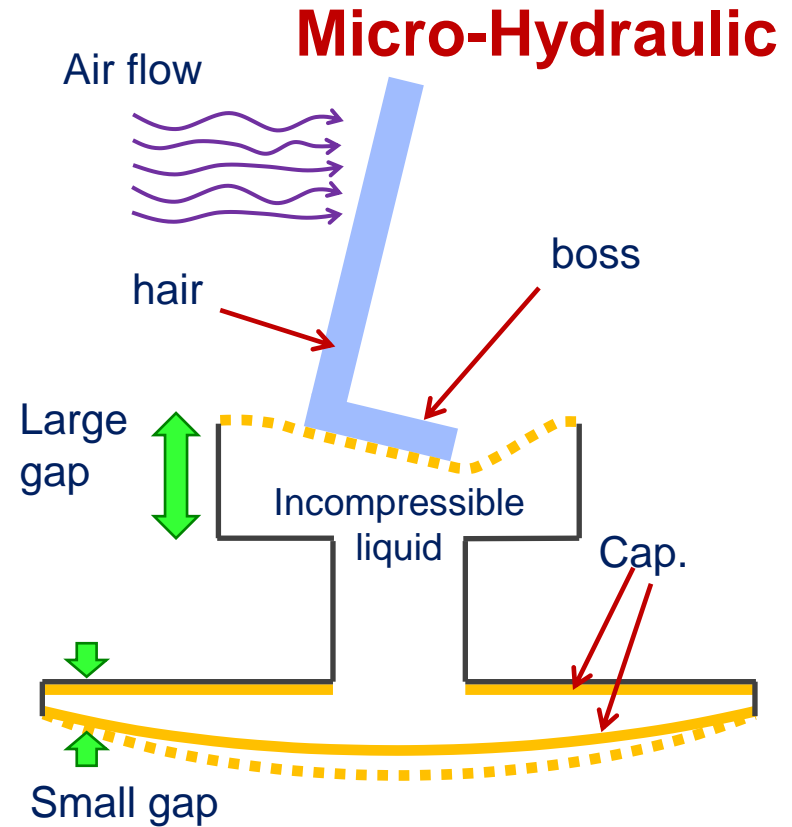
# Single Capacitive Flow Sensor vs. Micro-Hydraulic



**Single capacitor flow sensors  
force trade-off between  
sensitivity ↔ full-scale range**

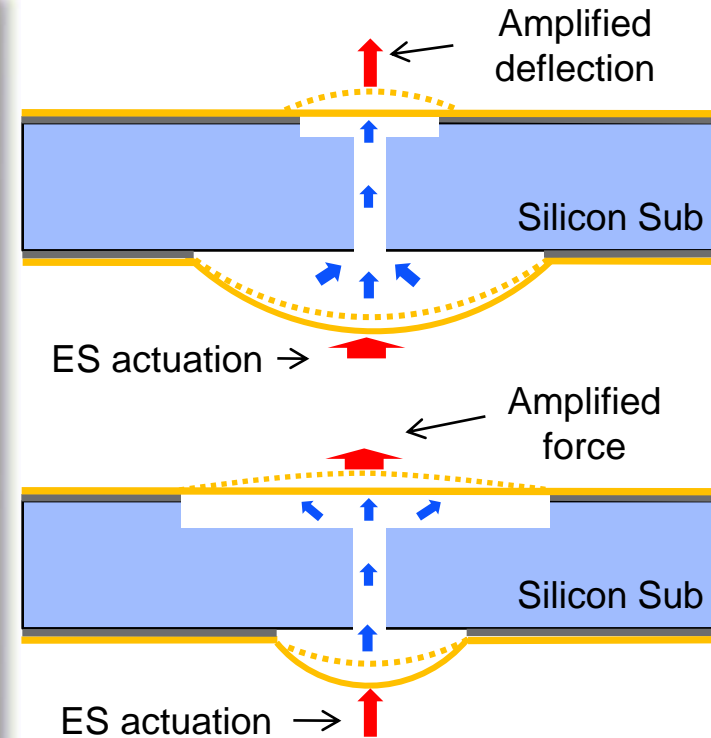
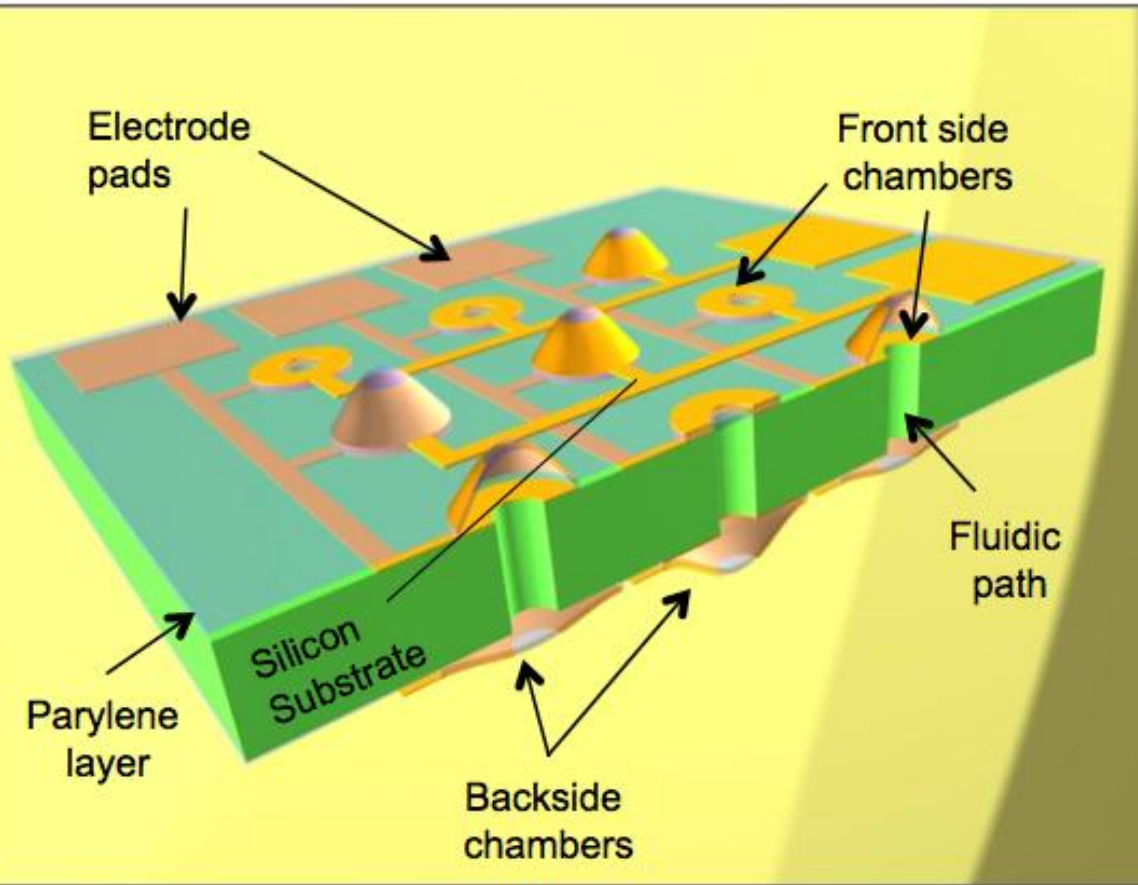


**Small single gap**



**High dynamic range, but  
viscous fluid flow reduces  
bandwidth**

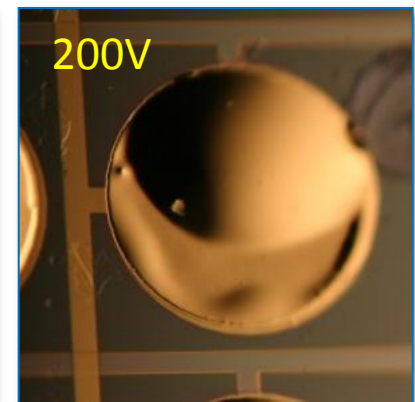
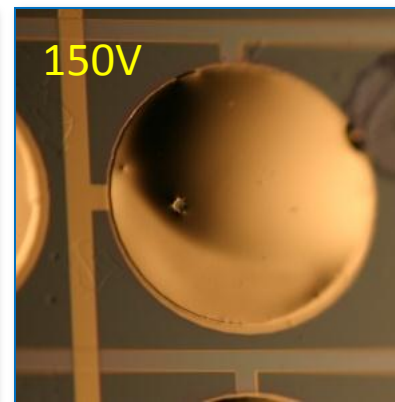
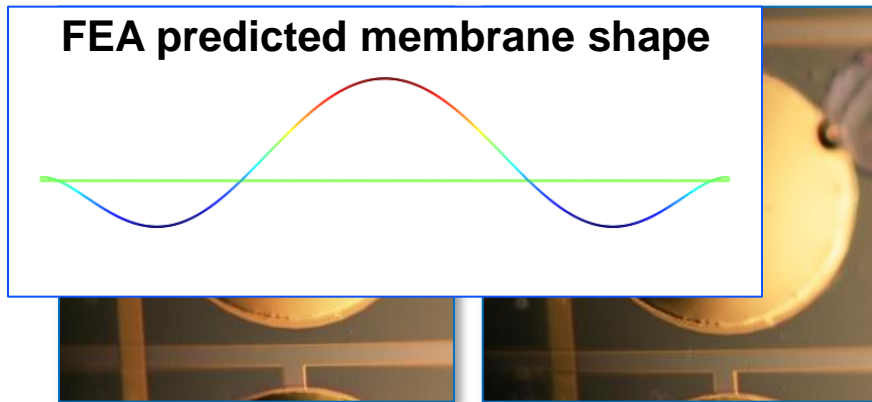
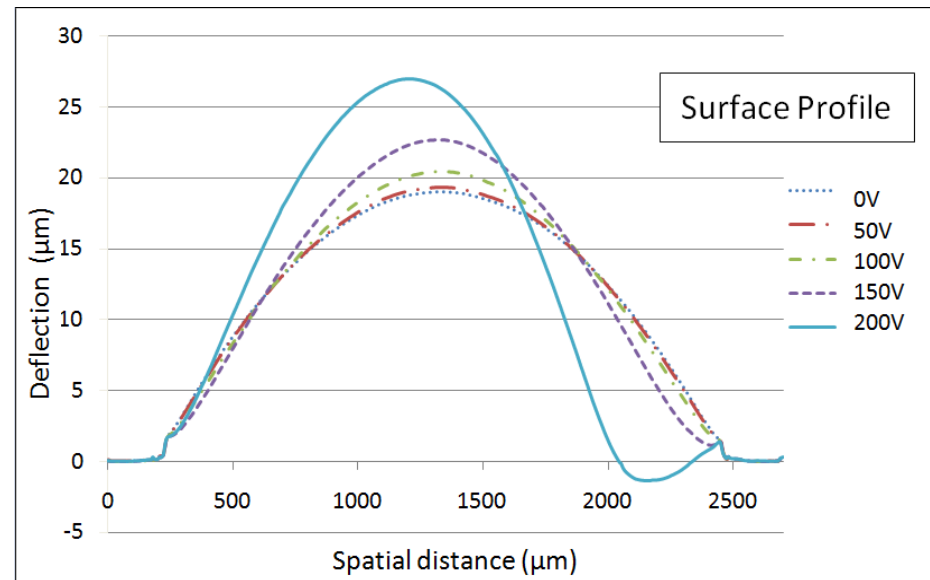
# Electrostatic Micro-hydraulic Actuation (EMA)



- Integrated electrostatic actuation, wafer-level process
- Array of individually actuated cells; addressability
- Hydraulic amplification for large-force/large-deflection actuation

# Experimental Results: Deflection vs. Voltage

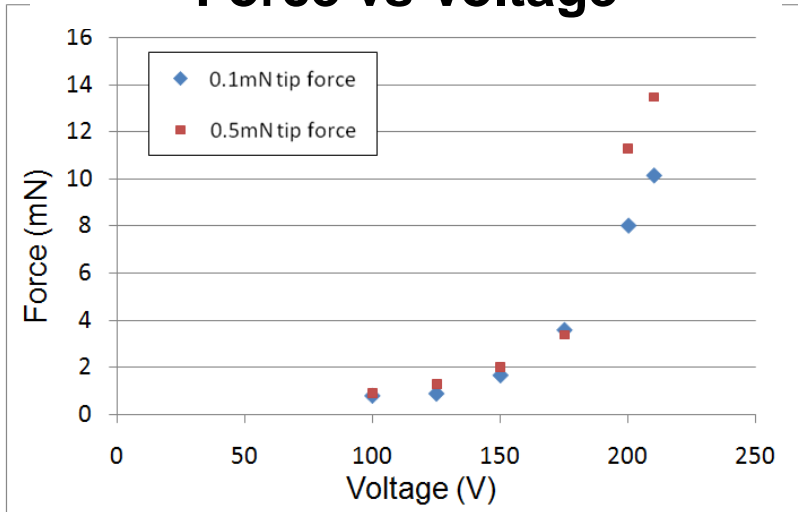
- Applied voltage 0-200V
- Bubble height is measured with profilometer; volume change confirmed by LEXT confocal microscopy
- Non-uniform deflection and asymmetric bulging due to edge pull-in



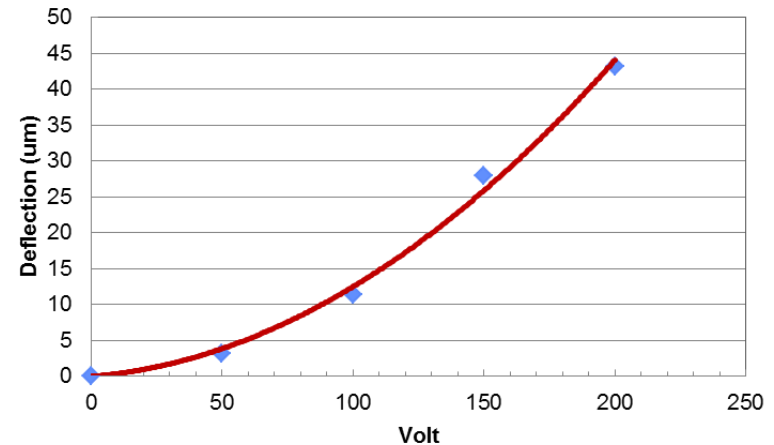
Optical images of one cell with  $D=2.2\text{mm}$  at 0, 100, 150 and 200V

# Experimental Results: Force, Power, Frequency

## Force vs Voltage

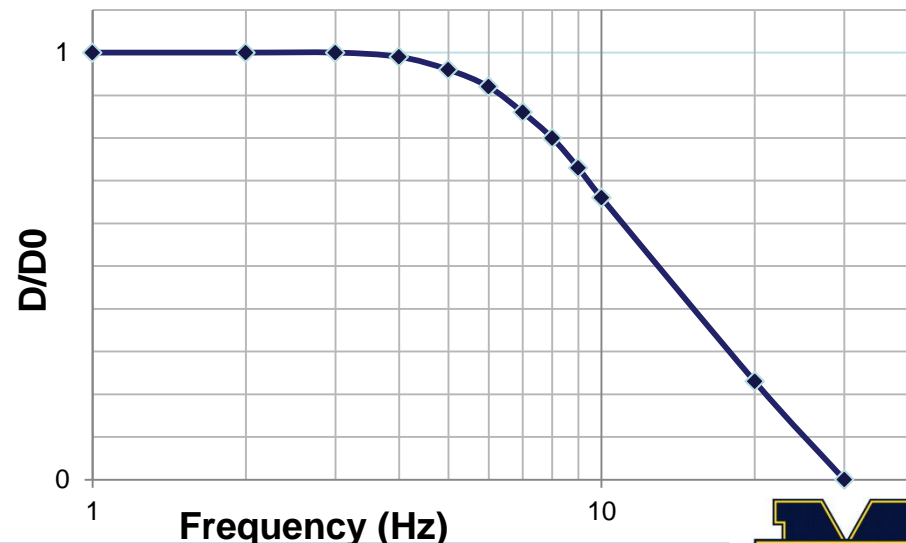


## Deflection vs Voltage



- Force > 12mN
- Deflection > 40 μm
- Power max 24 μW per cell per cycle
- Frequency: DC to 10 Hz (straight wall design)

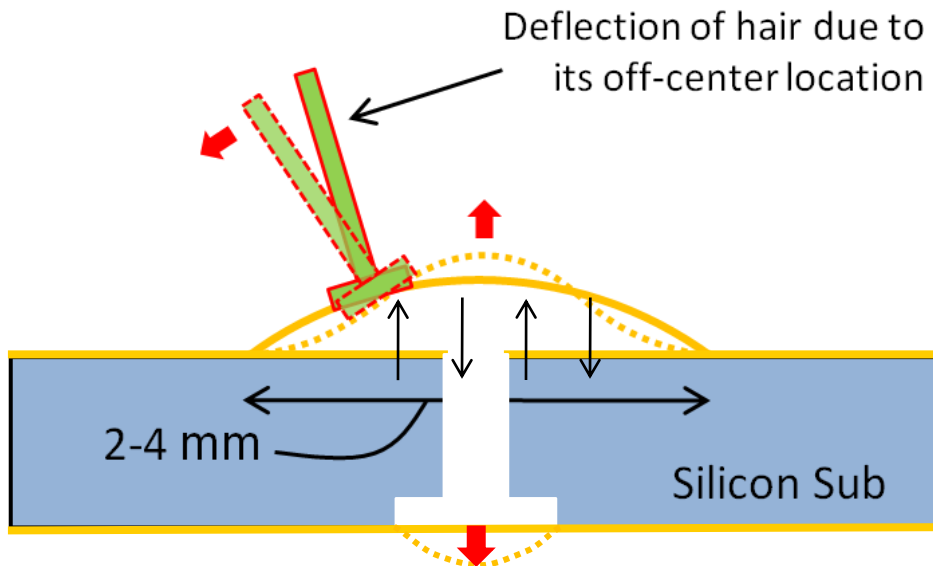
## Deflection vs. Frequency





# Actuation for Locomotion

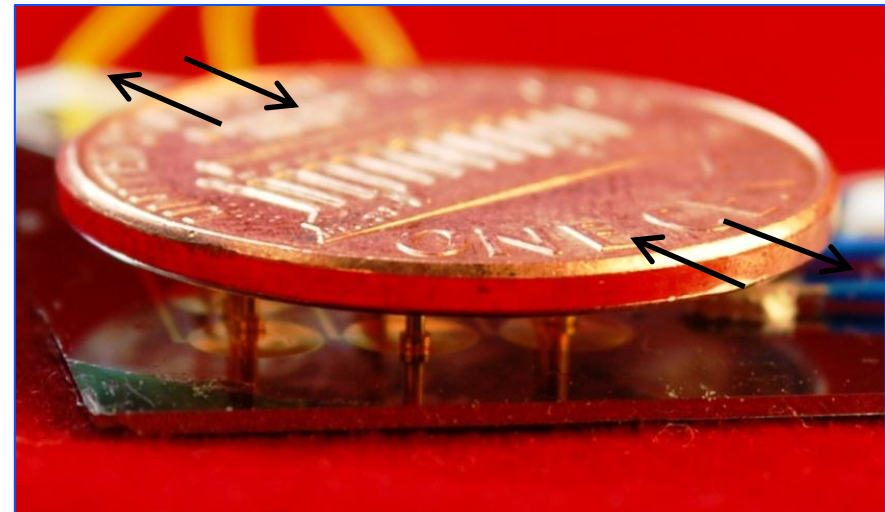
- Phase deflection of multiple membranes creates 'stride'; maximize deflection by off-center positioning of the cilia on membrane
- The device can carry  $\sim 5\times$  its own weight, almost 2.5 gram



2 Hz actuation

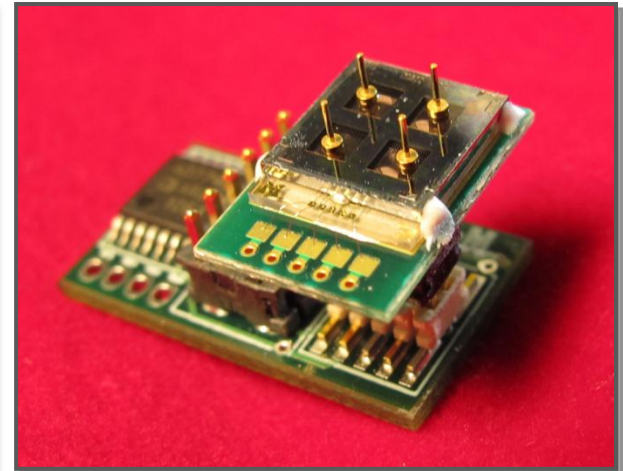
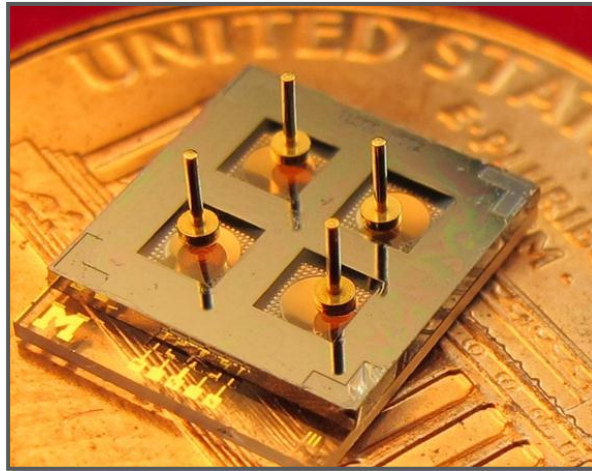


Hairs holding the coin



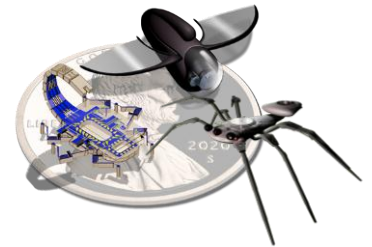
# Conclusions

- Novel wafer-level liquid encapsulation for HAIR-like sensing and actuation based on micro-hydraulic, electrostatic architecture  
→ new design element in MEMS
- Air flow sensors with record dynamic range and suitable response time for control loop insertion for MAST MAVs (work ongoing)
- High-force/high-deflection micro-hydraulic actuators
- Ongoing and future work on interface circuits, tactile sensing, air foil control, and other hair functionalization



# Acknowledgments

- This project is funded by the Micro Autonomous Systems and Technology (MAST) Program of the Army Research Lab under Award Number W911NF-08-2-0004.
- Dr. Will Nothwang, ARL Lead for Microelectronics Center of MAST
- Lurie Nanofabrication Facility, a member of the National Nanotechnology Infrastructure Network, supported in part by NSF
- Undergraduate researchers Bing Zhang and Michael T. Chaney



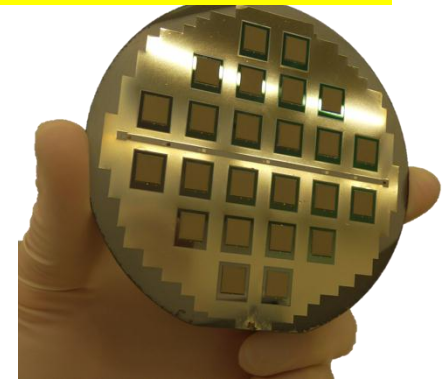
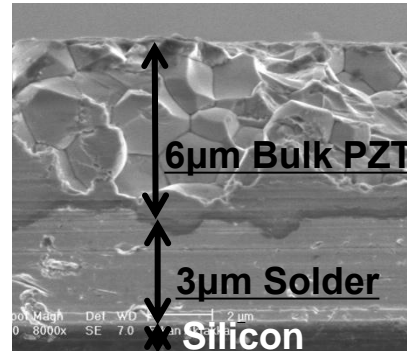


# Integration of Bulk Piezoelectric Materials

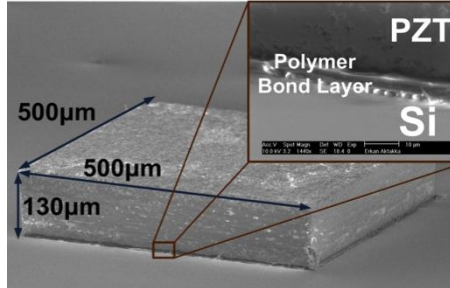
**Ethem Erkan Aktakka, Rebecca L. Peterson, Khalil Najafi**

**Aktakka, et al., Transducers'09, IEDM'10, PowerMEMS'11, HiltonHead'12**

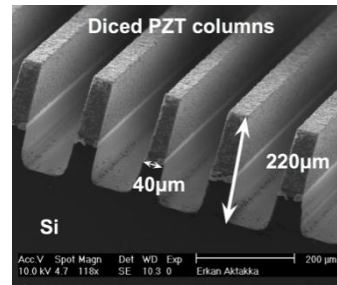
- Characterized bonding & lapping process
- Wide range thickness control (5-100 $\mu$ m)
- Wafer-level thickness uniformity ( $\pm 0.5\mu$ m)
- Conserved piezoelectricity & polarization
- Post-CMOS compatible process



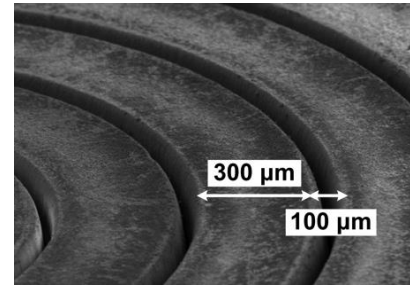
**Die-level bonding**



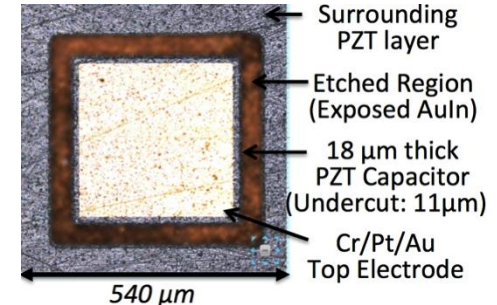
**Precision Dicing**



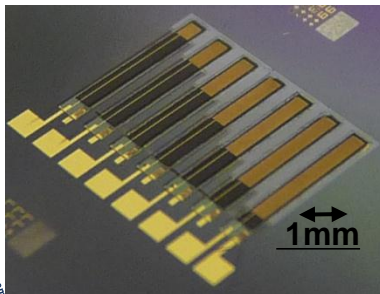
**Laser Machining**



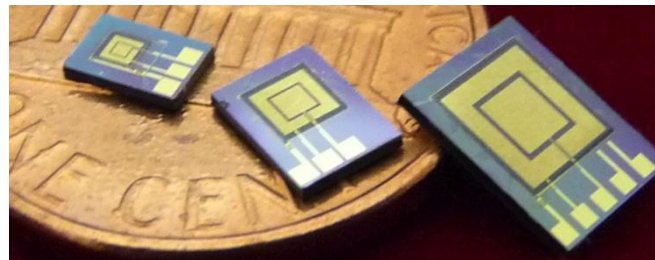
**Wet-Etch Patterning**



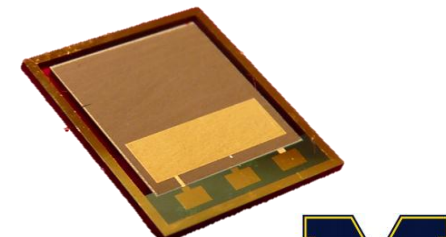
**Cantilever Actuators**



**Diaphragm Actuators**



**Micro Energy Harvesters**



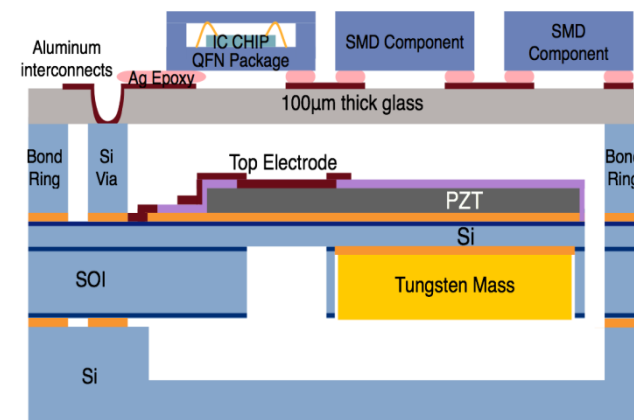
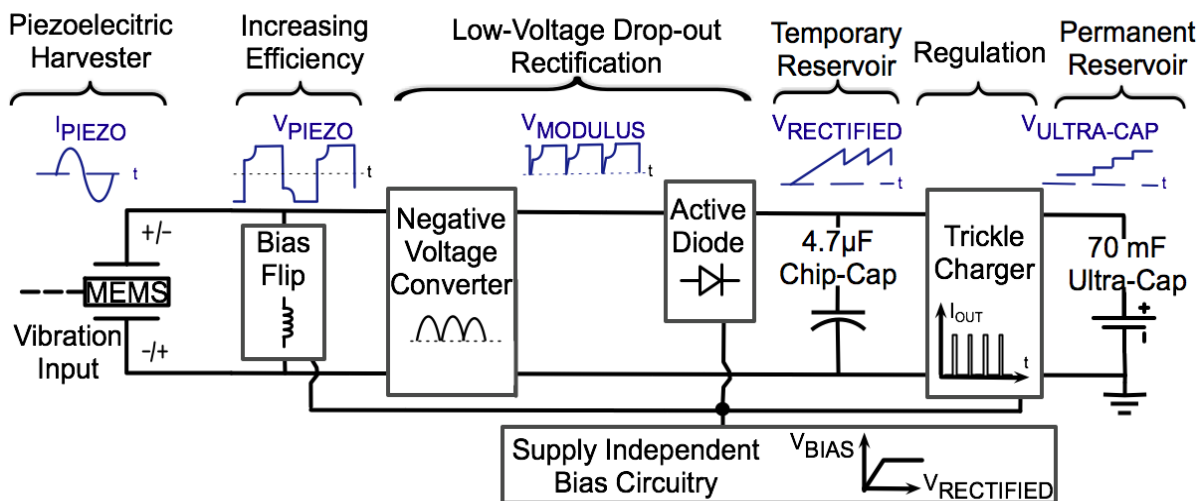
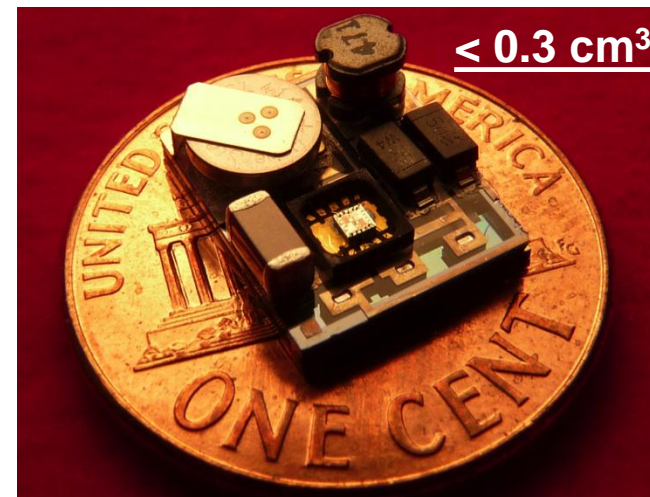
# Self-Supplied Inertial Piezoelectric Energy Harvester with Power Management IC

*Ethem Erkan Aktakka, Rebecca L. Peterson, Khalil Najafi*

**Goal:** Self-contained vibration energy harvester for industrial applications or vehicle instrumentation

## Results:

- High power density (205  $\mu\text{W}$  at 1.5 g vibration)
  - Large bandwidth (14 Hz)
  - Low frequency operation (155 Hz)
- Autonomous charging of an ultra-cap (0 V to 1.85 V)
- No requirement for a pre-charged battery/capacitor



**IEDM'10, ISSCC'11, Transducers'11**

**Funded by DARPA HI-MEMS**



# A Vibration Harvesting System and Electronics for Bridge Health Monitoring Applications

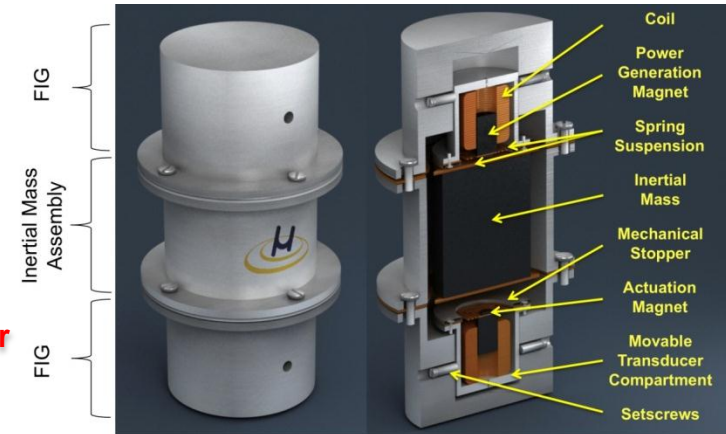
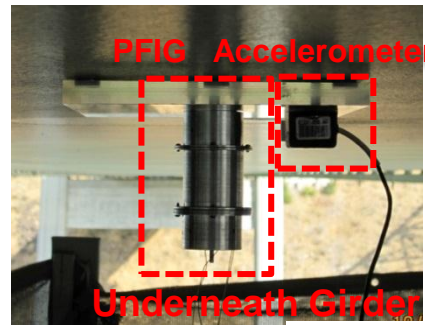
*James McCullagh, Tzeno Galchev, R. L. Peterson, and Khalil Najafi*

**Goal:** Harvest low-acceleration, low-frequency, non-periodic vibration energy from bridge to power wireless sensor network for structural health monitoring

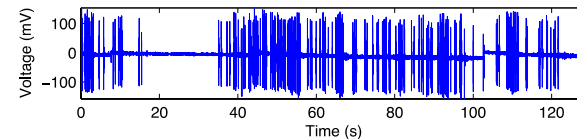
## Results:

- 5<sup>th</sup> Generation **Parametric Frequency Increased Generator (PFIG)** built
- Achieved record low threshold acceleration of 35mg ( $1g = 9.8m/s^2$ )
- Increased avg. power to 131  $\mu W$  at 11 Hz
- Testing PFIG + circuit on bridge to generate DC output voltage

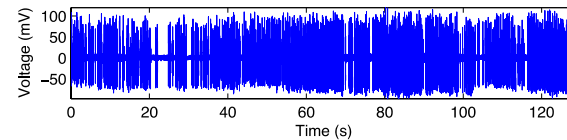
**Galchev, et al., J. Micromech. Microeng. 21, 1, 2011; Two papers at Transducers 2011; PowerMEMS 2010**



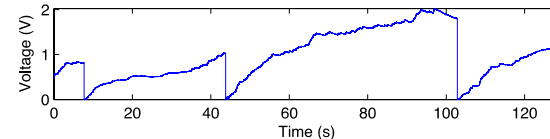
PFIG architecture and installation on suspension bridge



PFIG output voltage 1



PFIG output voltage 2



Storage Capacitor, (discharged manually)



# ***HAIR Based Sensing and Actuation***

**Mahdi M. Sadeghi, Becky (R. L.) Peterson, and Khalil Najafi**

*Electrical Engineering and Computer Science (EECS) Dept.  
University of Michigan*

The 2<sup>nd</sup> Multifunctional Materials for Defense Workshop  
August 1, 2012  
Arlington, VA